

Development of gallium-oxide (Ga2O3) coatings by nonaqueous sol-gel routes for electronic applications

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The University of New South Wales Faculty of Science School of Materials Science and Engineering

# Development of Gallium-oxide (Ga<sub>2</sub>O<sub>3</sub>) Coatings by Non-Aqueous Sol-Gel Routes for Electronic Applications

A Thesis

By

### Saeed Mohammadali

Submitted in Partial Fulfilment of the

Requirements for the Degree

Of

### **Master of Engineering**

In

**Materials Science and Engineering** 

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#### ABSTRACT

The overall aim of this thesis was to develop a sol-gel gallium oxide  $(Ga_2O_3)$  coating and to study the phase evolution in coating, and to evaluate theoretically the crystal structure and electrical properties of coating by modelling the intrinsic- and doped- $Ga_2O_3$  structure u sing Materials S tudio s oftware, and to solid theoretical re sult, experimental work was performed and compared with the simulation results.

The most stable phase of gallium oxide ( $\beta$ -Ga<sub>2</sub>O<sub>3</sub>) is a wide band gap (4.9eV) metal oxide ha ving a wide r ange of i mportant a pplications.  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> is thermally a nd chemically st able at hi ght emperatures and s o e xhibits very s table ope rating characteristics over large temperature ranges.

The major limitations of this coating arise from it having high resistivity. Monoclinic gallium oxide ( $\beta$ -Ga<sub>2</sub>O<sub>3</sub>) is one of the most promising materials for the device applications because of its wide band gap which gives high transparency from the visible i nto the UV wavelength regions (~260 n m). However, the high electrical resistivity of Ga<sub>2</sub>O<sub>3</sub> coatings is going to be a significant issue making limitation for this coating to be used in optoelectronic devices. Therefore, incorporation of dopants to reduce Ga<sub>2</sub>O<sub>3</sub> resistivity is desirable.

To de velop  $Ga_2O_3$  coating, two types of s ols were prepared in t his work using gallium isopropoxide as t he s tarting precursor. T he f irst s ol (Type-I so l) was prepared via an aqueous route based on the method developed by Yoldas for alumina sol-gel coatings. The other sol (Type-II sol) was prepared via a non-aqueous route involving 2-methoxyethanol (MOE) as the solvent. The principle of coating process was the deposition of these sols onto substrate (glass and quartz) by spin coating followed by drying and then heat treating at elevated temperature. The Type-I sol did not ge late d uring the d eposition process a s evidenced by the lack of any visible coating on the substrates. In c ontrast, the T ype-II s ol p roduced obvious coatings, albeit w ith va rying e xtent of c racking de pending on t he de position and he attreatment conditions.

In a nother stage of pr oject, the e ffects of t he coating t hickness, h eat t reatment conditions, and s ubstrate t ype on c oating s tructural e volution w ere i nvestigated. Phase c omposition in the Ga<sub>2</sub>O<sub>3</sub> sol-gel c oating w as s tudied a s f unction of he attreatment conditions. The initial deposited phase of gallium oxide transformed to  $\alpha$ -Ga<sub>2</sub>O<sub>3</sub> and then to  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> with increasing temperature. At 500°C,  $\alpha$ -Ga<sub>2</sub>O<sub>3</sub> phase started to form and upon heating at 900°C,  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> was only stable phase of gallium oxide. Subsequent heat treatment at different heating temperature for 2 h affected the coating be haviour in t erms of t he a mount of cracking. T he a mount of c racking tended to increase with increasing heating rate and with increasing coating thickness. The choice of substrates for Ga<sub>2</sub>O<sub>3</sub> was studied since it is critical and substantial for making high-quality coatings.

In this work, the effect of a dding different do pants on the electrical properties of gallium oxi de c oatings w ere i nvestigated t heoretically us ing s oftware cal led Materials Studio. The Modeling of  $Ga_2O_3$  showed that the introduction of the Sn and Zn caused the impurity energy level at the bottom of the conduction band. Therefore, the conductivity of the Zn-doped and Sn-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> was improved compared to the intrinsic  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>.

In order to assess the simulation result and obtain how much the results are close to the practical results, experimental work was carried out by measuring the bandgap of pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, Z n3%-doped G a<sub>2</sub>O<sub>3</sub>, a nd Zn6%-doped G a<sub>2</sub>O<sub>3</sub>. The study indicated that in s pite of a deviation in values be tween the experiment and s imulation, the values were considered fit well, and there was a consistency between simulation and experiment results.

It was found that the experimental value of the bandgap energy for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> agreed reasonably well with values reported in the literature and the experimental values for the pure and doped coatings were consistently ~2 times higher than the simulated values which suggested that the structural model u sed to calculate the bandgap energies systematically underestimated the values. This was attributed to limitations in the structural model. Regardless, the structural model was considered reliable for predicting the effects of dopants on selected s tructural and e lectronic properties of Ga<sub>2</sub>O<sub>3</sub>.

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#### 1. Introduction

#### 1.1 AIMS OF RESEARCH PROJECT

The major aim of the research project was to develop a convenient and reliable solgel coating technique for the deposition of polycrystalline pure- and doped-gallium oxide ( $Ga_2O_3$ ) on a morphous and c rystalline s ubstrates f or o ptoelectronic applications. P arallel to this was the major aim to theoretically model the crystal structure and electrical properties of pure- and doped-Ga<sub>2</sub>O<sub>3</sub> coatings to predict and understand the role of do pant cations in the semiconducting be haviour of Ga<sub>2</sub>O<sub>3</sub>. These ai ms w ere ach ieved by t he completion of t he f ollowing main ar eas o f research: study of the gelation behaviour of pure- and doped-Ga<sub>2</sub>O<sub>3</sub> coatings; study of the drying and f iring shrinkage characteristics so a s to m inimise/eliminate cracking in coatings and to optimise coating quality; study of the microstructural and phase evolution within the coatings as a function of he at-treatment c onditions (temperature and time) and substrate type (glass versus quartz); elucidation the phase transformation mechanism in the coating for the conversion of the initial gallium-oxide precursor (sol) to  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> during heat treatment; modelling of the effect of divalent a nd/or tetravalent s olid solution dopa nt cations (Sn, W, a nd Z n) on the crystal structure and electrical properties of Ga<sub>2</sub>O<sub>3</sub> using proprietary software; and experimental measurement of the bandgap energy of pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> sol-gel coatings and c oatings dope d w ith a s elected dopa nt (Zn) t o e nable c omparison w ith theoretical values given by the structural model. The research project consisted of four main stages of experimental work as shown schematically in Fig. 1.1.



Fig.1.1 Main stages of experimental work

#### 2. Literature Review

#### 2.1 INTRODUCTION

In this section, a pplications, properties, and l imitations of  $Ga_2O_3$  coating will be discussed. Then various techniques to fabricate this type of coating are explained, mostly sol-gel process which is the main technique of this work are discussed. At the end of this section, the effect of substrates and dopants on the properties of  $Ga_2O_3$  coatings fabricated by sol-gel technique is reviewed.

#### 2.2 Ga<sub>2</sub>O<sub>3</sub> COATING

#### 2.2.1 Applications

The most stable phase of gallium oxide ( $\beta$ -Ga<sub>2</sub>O<sub>3</sub>) is a wide bandgap (4.9eV) metal oxide having a wide range of important applications including a nti-reflection and passivation c oatings [1], semiconducting l asers [2], so lar cel ls [3], f ield-effect

devices [4], switching m emories [5], and high-temperature g as sen sors [6, 7].  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> is thermally and chemically stable at high temperatures and so exhibits very stable operating characteristics over large temperature ranges. For example,  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> has a monoclinic crystal structure at room temperature and this structure is retained at a ll t emperatures up t o the m elting point (~2000°C). F urthermore, unlike ot her metal oxides, no surface reduction of the Ga<sub>2</sub>O<sub>3</sub> occurs [8]. As a consequence of its high stability and w ide bandgap value, it is a promising m aterial for use in g as sensors at high temperatures and, for example, has used as a high-temperature (~800-1000°C) oxygen sensor [9, 10]. Since gas-sensing properties are expected to improve at l ower crystallite sizes ( due t o an i ncreased su rface ar ea), p roducing nanocrystalline to operate  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> in this temperature range is likely to be highly advantageous for this application. Also,  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> gas sensors have a short response time and a good sensitivity, which are desirable characteristics of a good gas sensor.

The interest in electronic and optical properties of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> has recently increased because of its potential applications as an ultraviolet transparent conducting ox ide [11]. Ga<sub>2</sub>O<sub>3</sub>-based glasses constitute an advanced class of optical glasses and have attracted i nterest a s a p hosphor m aterial f or a pplications in th in f ilm electroluminescent d isplays b ecause of i ts s ignificant l uminescence characteristics [12].

#### 2.2.2 Polymorphs of Ga<sub>2</sub>O<sub>3</sub>

Roy and Osborn [13] reported five polymorphs of  $Ga_2O_3$ :  $\alpha$ ,  $\beta$ ,  $\gamma$ ,  $\delta$  and  $\varepsilon$  phases. The occurrence and stability of the polymorphs are dependent on the conditions of preparation. Structural data and bandgap values of the  $Ga_2O_3$  polymorphs are given in Table 2.1.

**Table 2.1** Crystal s tructures, l attice p arameters, sp ace groups, and bandgap ofGa2O3 polymorphs [14, 15]

Phase	Crystal system	Lattice Parameters	Density (g/cm <sup>3</sup> )	Space group	Band-gap (eV)
α	Hexagonal	a= 0.498  nm c= 1.343  nm $\alpha= 120^{\circ}$	5.88	R3c	2.4
β	Monoclinic	a = 1.2214  nm b = 0.3037  nm c = 0.5798  nm $\beta = 103.83^{\circ}$	6.44	C2/m	4.9
γ	Cubic spinel	a= 0.822 nm	_	Fd3m	_
δ	Body Centred Cubic	a= 0.952 nm	_	Ia3	2.3
3	Orthorhombic	a = 5.12  nm b = 8.79  nm c = 9.41  nm	_	Pna2 <sub>1</sub>	_

 $\beta$ -Ga<sub>2</sub>O<sub>3</sub> is reported to be the most stable form of gallium-oxide and hence the most common form of the oxide. Although other phases exist, they tend to convert to  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> upon he ating a bove 870°C [16-18]. The  $\alpha$ -Ga<sub>2</sub>O<sub>3</sub> structure is a lowtemperature form below 600°C having a hexagonal crystal structure. The  $\gamma$ ,  $\delta$  phases are reported to have a cubic structure and bcc structure, respectively. The  $\gamma$ -phase is less clearly understood but it is known to show a spinel structure.  $\epsilon$ -Ga<sub>2</sub>O<sub>3</sub> was found to appear by heating  $\delta$ -Ga<sub>2</sub>O<sub>3</sub> at above 500°C [5]. Yoshioka *et al.* [19] calculated Helmholtz free en ergies of formation as a f unction of t emperature for the v arious phases of Ga<sub>2</sub>O<sub>3</sub> (see Fig. 2.1) and determined that the formation energies are in the sequence  $\beta < \epsilon < \alpha < \delta < \gamma$  at temperatures below 1400 K.



**Fig. 2. 1** Temperature dependence of t he d ifferences i n H elmholtz f ree en ergy between  $\beta$ - and other phases ( $\alpha$ -,  $\epsilon$ -,  $\delta$ -,  $\gamma$ -) [8]

The thermodynamic stability of the various  $Ga_2O_3$  polymorphs is reflected in their volume expansion characteristics in that, over the temperature range of ~298-1000 K, the values of the coefficient of thermal expansion increase in the order of  $\beta$ ,  $\varepsilon$ ,  $\alpha$ , and  $\delta$  (as shown in Fig. 2.2(a)). A similar trend exists below 400K Bulk moduli for the f our ph ases a re s hown i n pl ot 2( b). A s c an be not ed, the c alculated m oduli increase in the order  $\beta$ ,  $\varepsilon$ ,  $\delta$ , and  $\alpha$  below 400K (127°C).



Fig. 2.2 Temperature dependence of volume expansion (a) and bulk modulus (b) for  $\alpha$ -,  $\beta$ -,  $\delta$ - and  $\epsilon$ -Ga<sub>2</sub>O<sub>3</sub> [8]

From these plots, the relative stability for the five phases can be shown. According to this calculation, the  $\beta$ - phase is energetically the most stable phase at temperatures below 1500K (1227°C) and the  $\epsilon$ -phase is more stable than the  $\delta$ -phase at temperatures below 1600K (1327°C) [19].

#### 2.2.3 Limitations

In terms of Ga<sub>2</sub>O<sub>3</sub> coating applications, the major limitations of this coating arise from it having high resistivity.  $\beta$ -type monoclinic gallium oxide ( $\beta$ -Ga<sub>2</sub>O<sub>3</sub>) is one of the most promising materials for the device applications because of its wide bandgap (E<sub>g</sub>= 4.9 eV) which gives high transparency from the visible into the UV wavelength regions (~260 n m). However, the electrical resistivity of Ga<sub>2</sub>O<sub>3</sub> coatings are high which w ould be a pr oblem f or t hese c oatings to be c onsidered a s op toelectronic devices op erated at s hort w avelengths. Therefore, finding a way to r educe Ga<sub>2</sub>O<sub>3</sub> resistivity is desirable.

#### 2.3 CERAMIC COATING TECHNIQUES

The objective is to deposit a ceramic layer on a substrate (metal, ceramic, polymer) to produce a surface having properties di fferent to the bulk material. T he applications of coatings are num erous and i nclude tribology, he at i nsulation, corrosion resistance, electronics, opt ics, opt oelectronic, bi omedical, etc. Typically, the thickness of the layer various from a few atomic layers produced by vacuum deposition techniques up to a few millimeters.

Numerous techniques have been employed in the synthesis of gallium-oxide coatings including s puttering [20], c hemical va pour de position (CVD) [21], p ulsed l aser deposition (PLD) [22], solvent e vaporation [23], molecular b eam ep itaxy (MBE) [24], spray pyrolysis [25], and sol-gel deposition [10, 26-28]. These techniques are examined next.

#### 2.3.1 Vacuum Deposition

A large variety of ceramics can be deposited in vacuum (oxides, nitrides, carbides, and carbon-diamond) onto a similarly large variety of substrates. Vacuum deposition techniques can be classified into two main techniques: chemical vapor de position (CVD) a nd phys ical vapor de position (PVD) [21]. For bot h t echniques, t he formation of the thin coating can be broken down into three main stages (which can be sep arated or s uperimposed de pending on t he pr ocess) [21]. T hese t hree m ain stages th at a re im portant in the formation of the thin coating ar e as b elow: Production of the species to be deposited; transport of the species to the substrate; and deposition on the substrate and growth of the layer.

The two vacuum deposition techniques are examined separately below.

#### Chemical Vapour Deposition (CVD)

The technique consists of p roducing a l ayer, o n a h eated substrate, b y ch emical reaction starting from reactive species in the gas phase [29]. The reactive species can be discrete gases or generated from the decomposition of gas precursors. Typically, CVD de posited c oatings are chemically homogenous and de nse and have a goo d physical adhesion on the substrate.

The stages of process include substrate preparation, heating the substrate, substrate positioning and chemical deposition. To control the process, basic variables include temperature, pressure, and reactant activity. R eactions o ccur o ver a w ide range of pressures and temperatures. Component on ranging from microsizes to macrosizes can be coated by CVD.

An i mportant a dvantage of CVD methods is that they in volve relatively low fabrication t emperatures to produce c oatings having high melting points t hat a re otherwise difficult to fabricate by other methods because they require very high fabrication t emperatures [29]. However, a major disadvantage is that the material deposition r ate by C VD is very slow. The production of thick c oatings and monolithic bodies c an therefore be very time consuming and expensive. A nother problem is the method produces microstructures consisting typically of fairly large grains which lead to low intergranular strength, poor electrical transport properties, and ot her diminished properties. Thus, CVD methods are limited mainly to the formation of thin films and coatings.

#### **Physical Vapour Deposition (PVD)**

PVD is a technique similar to CVD for coating materials in a vacuum but involves the transport of vapour without any chemical reactions [30]. The coating material is vaporised from t he so lid or l iquid state w ith t he r esultant g aseous species b eing transported to the substrate where upon it condenses onto the surface by nucleation and growth. Vaporisation is performed by either evaporation or sputtering. The main evaporation m ethods a re di rect e vaporation, r eactive e vaporation, a nd a ctivated reactive evaporation. PVD coating process is performed in a v acuum chamber at a pressure of around 10<sup>-2</sup> and 10<sup>-3</sup> mbar. Advantages of PVD include the possibility to vary the substrate temperature; its versatility in composition of the deposit such as ceramic, pure metal or alloy; deposition of high purity coatings; and good bonding strength and ex cellent surface finish of coatings. D isadvantages of PVD processes include t hen be ing very c ostly a nd be ing c apable of only s hort v apour di ffusion distances.

Sputtering [25] is one of basic techniques of P VD. One a dvantage of this v apor phase t echnique is t he ve rsatility a fforded by t he pos sible use of multiple evaporation/sputtering s ources, t hereby pr oviding c onsiderable control ove r t he coating composition and phase pr ofile. H owever, va cuum conditions n ecessitate a confined space, which is not conducive to the cost effective handling of large area substrates. Sputtering techniques suitable for large area deposition require expensive vacuum equipment and sputtering targets.

#### 2.3.2 Pulsed Laser Deposition (PLD)

Pulsed laser de position (PLD) is a thin film de position technique utilising a high power pulsed laser beam focused inside a vacuum chamber to strike a target of the material that is to be deposited [31]. This material is vaporized from the target which then deposits as a thin film on a substrate. This p rocess c an o ccur i n u ltra-high vacuum or in the presence of a background gas. For example, for the latter oxygen is commonly us ed w hen depositing o xides t o ensure that the de posited coatings ar e fully oxygenated. While the principle and basic setup are simple and similar to other gas deposition t echniques, the phys ical phe nomena of l aser-target in teraction a nd coating gr owth a re qui te c omplex. The a dvantages of pul sed l aser de position a re flexibility, fast r esponse, en ergetic ev aporants, an d congruent e vaporation. Disadvantages of t his process are t hat small coating areas (limited u niformity), formation of particulates, and target surface modification [31].

#### 2.3.3 Ion Implatation

Ion implantation is a popular technique to improve the wear resistance and corrosion resistance of materials. It is a process in which chosen atomic species are ionized and then acce lerated in an electric field u nder a m oderate v acuum and fired i nto t he surface on the substrate. Coatings can be produced as thick as ~1  $\mu$ m [32]. Process variables include i on dos e, dos e r ate, substrate t emperature, and an nealing temperature. Ion implantation rates range be tween 10<sup>10</sup> ion/cm<sup>2</sup> for semiconductor doping and 10<sup>19</sup> ion/cm<sup>2</sup> for surface chemical conversion. Continuous or sequential processes o f de position a nd i on b ombardment a re pos sible by a daptation of t he

implantation e quipment. A dvantages of i on i mplantation i nclude: m inimisation of thermal di stortion of pr ecision c omponents by implantation a t l ow t emperatures; absence of an i nterface w hich e liminates de bonding due t o m echanical s tress o r corrosion; and improvement of surface finish by sputtering erosion of the substrate. In addition, considerable biaxial compressive stress can induced in the surface layers and can ev en b e u sed t o cl ose s urface m icro-cracks i n cer amic materials [33]. Disadvantages o f t his p rocess are that i t r equires ex pensive equipment and y ields very low deposition rates.

#### 2.3.4 Spray Pyrolysis

This t echnique i nvolves he ating a pow der m aterial t o n ear i ts m elting poi nt t o partially melt the particles and then accelerating the particles in a h igh velocity gas stream t o project them against the substrate to be c oated. Spray pyrolysis us ually gives little significant heating of the substrate [12]. It is carried out in gas plasma, formed typically by ionizing a gas by arc discharging between a tungsten cathode and a c opper a node. T he i nitial g as us ed i s a n i nert ga s ( argon or he lium) a nd secondary gas may be added. The temperature in the centre of the plasma column exceeds 30 000°C and this high temperature causes a rapid expansion of the gas thus producing t he hi gh ve locity a nd h igh t emperature s pray gas s tream needed f or particle melting and deposition of the powder. Advantages of this coating technique include the ability to deposit thick coatings of uniform coverage at high deposition rates. However, the process is line of sight and coatings tend to have a higher amount of residual porosity as well as greater roughness compared with other techniques.

#### 2.3.5 Sol-Gel Processing

Sol-gel processing is a type of c olloidal processing route that is us ed to fabricate ceramic c omponents in both bulk and c oating forms [34]. A c olloidal s uspension may be defined as a dispersion of particles, each particle in the range of 1 to 1000 nm in at least one dimension, in a continuous liquid medium. C olloidal be haviour governed b y the in teractions between di spersed particles w ithin the s uspending medium. A distinguishing feature of such colloidal s ystems is the large interfacial area between the particles and the medium, and the development of surface charge on t he p articles, and t hese s trongly i nfluence characteristic p article-particle interactions such as agglomeration [35, 36].

Sol-gel coatings generally are thin films deposited on s olid substrates from a liquid solution via the following steps: (a) preparation of the sol, (b) formation of coating layer on s ubstrate, (c) drying the sol to a gel, and (d) firing of the coating layer on substrate. A sol is a dispersion of solid particles in a liquid phase where the particles are small enough (approximately  $0.1-1 \mu m$ ) to remain suspended. A gel is a solid containing a liquid component in an internal network structure so that both the liquid and solid are in highly dispersed state. In the gel state, material can be shaped into a useful pr oduct, e .g. bu lk shape, c oating, f ibre, e tc. I n the sol-gel p rocess, t he precursors a re s tarting c ompounds for pr eparation of a c olloid c onsist of a metal surrounded by va rious ligands. T hese l igands a re e ither organic c ompounds or inorganic salts such as alkoxide or nitride compound, respectively.



Fig. 2.3 Flow chart for sol-gel processing

Metal al koxides ar e p opular p recursors b ecause t hey react r eadily w ith w ater (solvent). T he r esultant s olution i s t hen hydr olysed t o f orm a hi gh-quality hi ghpurity nano-cluster sol, and subsequently a gel [37]. Additives can also be added to control the viscosity and surface tension of the sol-gel to aid in the coating process. Colloidal dispersions (sols) are prepared by peptisation (with a mineral acid such as HNO<sub>3</sub>), while a gelis formed by de hydration or pH control. S ol-gel processing includes aqueous-based processes that start from a solution of metal salt and alcoholbased processes that derive from a metal alkoxide. In the aqueous-based process, sol formation is a complished by hydr olysis of t he m etali ons, i .e.  $M^{n+} + nH_2O \rightarrow M(OH)_n + nH^+$ .

Gelation of t he so l i s accomplished b y ei ther t he r emoval of w ater (dehydration gelation) or an increase in the pH (alkaline gelation). As water is removed during dehydration gelation, the energy barrier to gelation is r educed by the increase in electrolyte concentration in diffuse layer. In alkaline gelation, an increase in the pH reduces the magnitude of positive surface charge on the sol particles, which reduces the repulsive force b etween p articles and l owers t he h eight of t he energy b arrier. Compaction of the gelled coating during drying, as driven by c apillary pressure, is resisted by aggregation due to gelation. Since colloidal (sol) particle compacts have very hi gh s urface e nergies, s intering c an be done a t temperatures well be low required for t he c orresponding c eramic pr epared by t radition pow der c ompaction techniques. Formation of sol-gel coatings on s ubstrates are performed by spin, dip, spray coating, or painting onto an appropriate substrate. The coated substrate is then fired t o r emove t he w ater and o rganic m aterial and t o d evelop t he final cer amic phase composition and microstructure in the coating [37, 38].

As indicated in flow chart (Fig. 2.3), the main sequence of steps in the solution solgel route has been outlined. The starting material normally consists of a solution of metal alkoxides in an appropriate solvent (water, alcohol, etc.). Metal alkoxides have the general formula  $M(OR)_x$  and can be considered as either a derivative an alcohol, ROH, where R is a n a lkyl group, in which the hydroxyl proton is replaced by a metal, M, or a derivative of a metal hydroxide,  $M(OH)_x$ . Under constant stirring at temperatures s lightly a bove ro om te mperature (n ormally 50 - 90°C) and w ith suitable c oncentration of r eactants a nd pH of t he s olution, h ydrolysis and condensation reactions may occur, leading to the formation of polymer chains.

For Gallium-aloxides, Ga(OR)<sub>3</sub>, the reactions may be expressed as:

**Hydrolysis:**  $Ga(OR)_3 + H_2O \rightarrow Ga(OR)_3 + ROH$ 

**Condensation:**  $Ga(OR)_2(OH) + Ga(OR)_3 \rightarrow (RO)_2 \cdots M - O - M \cdots (OR)_2 + ROH$ 

*Polymerization* of the species formed by the hydrolysis and condensation reactions together with interlinking and cross-linking of the polymer chains eventually leads to a marked increase in the viscosity of the reaction mixture and the production of a gel. The gel has a continuous solid network and a finite shear modulus.

*Drying:* The remainder of the volume consists of liquid that must be removed prior to firing. Drying of the gels can be the most time consuming and difficult step in the overall fabrication route. Normally, the liquid is present in fine channels, typically 2-50 nm diameter. Removal of the liquid by evaporation has two main consequences: large capillary stresses are generated, and the gel undergoes considerable shrinkage under the action of the capillary stress. That is why there is a huge amount of crack after drying. Aging be fore drying helps to strengthen the gel network and thereby reduce the risk of fracture.

#### 2.3.6 Comparison between Ceramic Coating Techniques

In this work, a sol-gel technique is utilised to make  $Ga_2O_3$  coating. For oxides such as  $Ga_2O_3$ , the sol-gel process has several advantages over other fabrication methods including: it is a more convenient and cost effective process; it is easier to control the composition of the coating and to produce the coating with pur ity and superior uniformity; it permits co ating of complex g eometries of irregular-shaped components; and, it g ives good c ontrol of m icrostructure; it involves lower preparation temperatures compared with other techniques [37]. Also, incorporation of dopants into coating formulations is simple and relatively large areas of substrates can be coated [39].

As an example shown in Table 2.2, Bae [40] evaluated ceramic coating prepared by various methods such as PVD, CVD, ion implantation, spray pyrolysis, and sol-gel in t erms of bonding s trength with substrate, coating hardness, s urface r oughness, thickness c ontrol, and c ost. This evaluation suggested that the sol-gel technique is scored higher than the other methods.

Properties (Weighting)	PVD	CVD	Ion Implantation	Spray Pyrolysis	Sol-Gel
Bonding strength	****	****	****	***	****
Coating hardness	****	****	****	***	****
Surface roughness	****	****	****	***	****
Thickness control	***	***	**	****	**
Cost	***	****	**	****	****
Evaluation	0.78	0.81	0.76	0.70	0.82

 Table 2.2 Evaluation of various ceramic coating methods for deposition of oxides
 [33]

\*:20%, \*\*:40%, \*\*\*:60%, \*\*\*\*:80%, \*\*\*\*:100%

#### 2.4 COLLOIDAL BEHAVIOUR

A colloid consists of two distinct phases: a continuous phase and a dispersed phase. The two phases may be solids, liquids, or gases, gi ving rise to various types of colloidal systems. The dispersed particles generally have dimensions ranging between 1 and 1000 nm [35]. In the processing of ceramics, colloidal suspensions (sols) consisting of a dispersion of solid particles in a liquid, a re of particular interest. The size of the polymer molecules in solution falls in the colloidal size range so that these systems are considered part of colloid science. Colloidal behavior is the interaction be tween the dispersed particles and the suspending medium [36]. A distinguishing f eature of a colloidal system is that the large interfacial a reab etween the particles and the medium, and the development of surface charge on the particles, controls characteristic particle-particle interactions such as agglomeration or flocculation.

#### 2.4.1 Stabilization of Colloidal Suspensions

A ba sic pr oblem underlying s ol-gel pr ocessing is the s tability of c olloidal suspensions. Obviously the particles should not be too large otherwise gravity will make sedimentation occur m ore qu ickly. Another important consideration is the attractive force between the particles. Attractive van der Waals forces exist between particles r egardless of whether o ther forces are p resent. If the a ttractive force is large, the particles will collide and agglomerate together (flocculate) leading to rapid settling of the particle clusters [36]. Most techniques employed to prevent flocculation r ely on t he i ntroduction of r epulsive f orces by r epulsion be tween electrostatic c harges (electrostatic s tabilization), re pulsion b etween p olymer molecules (steric st abilization), or so me c ombination of t he t wo (electrosteric stabilization). A s table c olloidal s uspension may be c onsolidated i nto a d ensely packed structure; however, an unstable flocculated suspension may lead to a loosely packed structure or, under certain conditions, to a particulate gel with a relatively low density [36, 37]. The motion of the particles when subjected to an electric field (electrophoresis) can be a source of valuable information for determining the surface charge of the particles. Colloidal suspensions, especially concentrated suspensions, also have remarkable r heological properties. A good pa int must flow easily when applied to the surface to be painted but then must become rigid enough to prevent it from flowing off a vertical surface. In ceramic processing, the rheological behavior of the suspension can be used as a direct process parameter to control and optimize the structure of the green body produced by the consolidation process [41].

#### 2.4.2 Rheology of Colloidal Suspensions

The term *rheology* refers to the deformation and f low characteristics o f m atter. Rheological measurements monitor changes in flow behavior (strain) in response to an applied stress. R heological m easurements ar e w idely u sed t o characterize t he properties of colloidal suspensions [36]. They can be used as a method of analysis as, for example, by measuring the viscosity of the suspension to determine the optimum concentration of di spersant required to stabilizing a su spension. Rheological measurements ar e a lso used commonly as a quality control t echnique t o m inimize the ba tch-to-batch v ariation of suspension pr operties pr ior to coating a nd consolidation. F urthermore, r heological m easurements can b e u sed as a d irect processing p arameter for t he c oating i n t hat the s uspension should have a l ow enough viscosity to enable it can to be cast into the desired shape [35, 36].

#### 2.4.3 Effect of Solvents

A solvent can affect chemical reactivity with an effect on solubility and stability, and choosing the appropriate solvent allows for thermodynamic and kinetic control over a chemical reaction [42]. The process of dissolution depends upon the free energy change of bot h the solute a nd the solvent. The free energy of s olvation is a combination of several factors. Firstly, a cavity must be created in the solvent. The creation of the c avity will b e enthalpically and entropically unfavorable a s t he ordered s tructure of t he solvent increases a nd t here are f ewer so lvent-solvent interactions. S econdly, the solute m ust separate out from the bulk s olute. This is enthalpically unfavorable a s s olute-solute i nteractions a re br eaking but is

entropically favorable [42,43]. Thirdly, the solute must occupy the cavity created in the solvent. This results in favorable solute-solvent interactions and is also favorable as the mixture is more disordered than when the solute and solvent are not mixed. Dissolution of ten oc curs w hen t he s olute-solvent in teractions a re s imilar to th e solvent-solvent interactions, s ignified by t he term like dissolves like. Hence, polar solutes di ssolve i n pol ar s olvents, w hereas nonpol ar s olutes di ssolve i n nonpol ar solvents. There is no one measure of solvent polarity and so classification of solvents based on p olarity can be car ried out u sing d ifferent s cales. Different so lvents c an affect th e equilibrium c onstant of a re action and the equilibrium is shifted in th e direction of the substance that is preferentially stabilized [44].

The chemical reactions involved in the sol-gel processing of  $Ga_2O_3$  involves gallium isopropoxide as a solute and methoxyethanol (MOE) and/or water as the solvent. The ability of MOE or water to solvate whatever solvent species depends on their relative acidity/basicity (i.e., the ionization equilibrium of the solvent) as well as the magnitude of the polar charge of each of them relative to that of the solute. This can be considered in terms of the (relative) dielectric constants of the solute and solvent species. The relative dielectric constant of water (78 at 20°C [45]) is significantly greater than that of MOE (17.2 at 20°C [45]) which indicates that the water is the more polar species and therefore is the solvent which should give faster and more complete solvation of the polar gallium isopropoxide solute.
# 2.4.4 Essential Requirements for Ga<sub>2</sub>O<sub>3</sub> Coatings

In ge neral, a sol s hould be a homogeneous l ow-viscosity l iquid without having tendency for sedimentation or phase separation. A sol that is potentially suitable for the formation of films or coatings should have the following general characteristics [27,46]: (1) thickness u niformity; (2) c ompositional h omogeneity; (3) s tructural homogeneity; (4) ability to form crack-free coatings. In addition, sol gel coatings for electronic services in particular should be transparent in the visible light range [1].

The essential requirements of  $Ga_2O_3$  coating for use in the electronic services more specifically in h igh-temperature a pplications include [9]: (1) be ing theoretically dense and free from any cracks and porosity; (2) being well-bonded to the substrate to prevent interfacial cracking and coating delamination in service; and (3) correct microstructure including phase composition, grain size, etc.

### 2.5 SOL-GEL PROCESSING OF Ga<sub>2</sub>O<sub>3</sub>

 $Ga_2O_3$  sols can be prepared through two different routes based on either an aqueous solvent (Type-I) [38] or a non-aqueous solvent (Type-II) [46,47]. In both types, gallium isopropoxide (GaP) is used as the starting material (precursor). The main stages involved in the processing in each route are summarised in Fig. 2.4.



Fig. 2.4 Flow chart for sol-gel processing of Ga<sub>2</sub>O<sub>3</sub>

In Type-I, as a new technique based on Y oldas [38], GaP dissolved in the MOE is hydrolysed with w ater. T his s tage i s done t he s ame a s Yoldas t echnique. T he

solution is stirred for a while to obtain an opaque white solution. The pH of this solution is measured and ad justed to 2 -3 by adding H NO<sub>3</sub>, the sam e as Y oldas technique. This stage is called P eptisation and followed by s tirring at temperature between 50-90°C for at least 1 h t o become a transparent colloid solution. In this technique, the molar ratio of precursor, solvent, and acid is important and should be considered according to Yoldas technique [38].

In Type-II, 2-Methoxyethanol (MOE) and monoethanolamine (MEA) are used as the solvent and stabilizer, respectively. GaP is dissolved in a mixture of MOE and MEA at temperature b etween 5 0-90°C followed by s tirring f or 1 h to obt ain a homogeneous and transparent solution [46,47].

These processes (Sol types I and II) are performed in a seal ed flask immersed in a controlled-temperature s ilicon-oil ba th. Then t he sols are spin c oated on t he substrates and as indicated in Fig. 2.4 the gelation stage, drying, and s intering are done [38, 47].

# 2.5.1 Phase Evolution with Heat-Treatment

Depending on the particular chemical preparation route, gallium-oxide can exist in a variety of oxide a nd hy drated oxi de forms [23]. Heat t reatment of t hese p hases converts them to the thermodynamically stable phase of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> via one or more metastable transition phases including  $\alpha$ -,  $\gamma$ -,  $\delta$ -, and  $\epsilon$ -Ga<sub>2</sub>O<sub>3</sub>. The s ol-gel phase produced b y t he non -aqueous/aqueous r outes f rom ga llium a lkoxide p recursors i s usually Ga OOH [48,49]. The t ransition sequence f rom GaOOH v ia various metastable gallium oxide phases to  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> is shown in Fig. 2.5.



**Fig. 2.5** Transformation relationships among the forms of Gallium oxide and its hydrates [13]

Roy and Osborn [13] reported that an  $\alpha \rightarrow \beta$  transformation occurs at 300°C under wet conditions and at 600°C under dry conditions,  $\varepsilon \rightarrow \beta$  transformation at 870°C under dr y atmosphere, and a  $\delta \rightarrow \varepsilon$  transformation at above 500°C under dr y atmosphere (Fig. 2.5).

# 2.5.2 Effect of Substrate

The choice of substrates is critical and substantial for making high-quality coatings. Basic considerations i nclude c rystallographic lattice m atch, co mpatible t hermal expansion, and solid-solubility between the coating and substrate. The lattice match between substrate and coating at the deposition temperature, as well as similarities in the crystal structure of substrate and coating, favor epitaxial coating growth [35, 36]. Usually, quartz and alumina have be en considered as substrate for  $Ga_2O_3$  coating, however from the relevant phase diagrams in Fig. 2.6, it can be seen that  $Al_2O_3$  is a better choice for substrate than  $SiO_2$ . The reason is that beside of crystal structure similarity between  $Ga_2O_3$  and  $Al_2O_3$ , they have a good s olid-solution s olubility in each other, which gives the possibility of forming a compositionally-graded interdiffusion bond 1 ayer. It is considered that s uch a bond 1 ayer will give excellent coating adhesion though minimization of the stress discontinuity at the interface [50, 51].



Fig. 2.6 Ga<sub>2</sub>O<sub>3</sub>-SiO<sub>2</sub> and Ga<sub>2</sub>O<sub>3</sub>-Al<sub>2</sub>O<sub>3</sub> phase diagrams [50]

# 2.5.3 Inter-diffusion between Coating and Substrate

In the development of a ceramic coating, the heat treatment conditions (primarily temperature and time) are very important in that they a ffect the formation of the bond, densification and microstructural evolution of the coating, and the resultant properties of the substrate such as coating adhesion, strength, and surface roughness [36]. In the case o fa  $Ga_2O_3$  coating on a n a luminal substrate, a n i ncrease i n temperature and heating time can affect the interface of coating and substrate by Al

diffusion i nto c oating and G a di ffusion i nto s ubstrate. Inter-diffusion be tween coating and substrate can be investigated by measuring the concentrations of Ga, Al, and O a s a function of de pth from the c oating surface us ing X -ray phot oelectron spectroscopy (XPS) [51]. In this work because the specific aim is the investigation of phase evolution in coating independent of substrate, this experiment is not run.

### 2.5.4 Incorporation of Dopants

In sol-gel technique, incorporation of dopants is easy and large area substrates can be coated readily [10]. However, the nature and content of dopants have a significant effect on the sol g el p rocess. Doping m ay dr amatically c hange the e lectrical properties of metal-oxide coatings. The r esistivity of the  $Ga_2O_3$  coatings can be tailored with different dopant and the concentrations. In addition, doping can affect the c rystalline s ize. I n this w ork, the e ffect of s ome dopa nts on ga llium oxi de coatings were investigated theoretically using software called Materials Studio. Also, to investigate w hich i ons c ould be suitable as dopant for  $Ga^{3+}$  in terms of s ol-gel process, doping solution of these ions with  $Ga^{3+}$  were made. Obviously, the reaction of compatible dopants with  $Ga^{3+}$  should lead to a homogenous solution.

In this work, to dope  $Ga_2O_3$  sol with different concentration of dopants, the dopants which w ould be c ompatible w ith  $Ga_2O_3$  were c onsidered. In particular, an i onic / covalent radius of the dopant cation should be close to gallium, thus the dopant ions could go i nto the lattice as substitutional dop ants. B ased on t his factor and from Pauling's ionic and covalent radii d ata, S n<sup>4+</sup>, Zn<sup>2+</sup>, and W<sup>6+</sup> ions were chosen as dopants for Ga<sup>3+</sup>.

### Electronegativity Role

Before studying the electrical properties of G  $a_2O_3$ , a key factor which affects the electrical p roperties o f metal o xides sh ould b e ex plained. T his f actor i s electronegativity differences which drive charge transfers on molecule formation. In particular, in sol-gel technique which chemical reactions occur during the process, electronegativity is a significant factor which influences the electrical properties of resultant c oating. It is the chemical potential of density functional theory. While energy and not electronegativity d etermines whether a chemical bond w ill form, electronegativity differences d etermine the charge transfers which occur on bond formation [36]. The method used for the preparation of a metal alkoxide depends, in general, on the electronegativity of the metal. The main methods may be divided into two groups: (1) reactions between metals and alcohols for the more electropositive metals (i. e., th ose w ith re latively l ow e lectronegativity v alues) and (2) re actions involving metal c hlorides f or the less e lectropositive metals or e lectronegative elements (i.e., those with relatively high electronegativity values).

The physical properties of metal alkoxides depend primarily on the characteristics of the m etal (e.g., t he e lectronegativity, valence, a tomic r adius, and c oordination number) and secondarily on the characteristics of the alkyl group (e.g., the size and shape). Therefore, a s di scussed e lectronegativity of metal i n m etal a lkoxide involving in the chemical reaction plays a big role and should be considered.

### 2.6 ELECTRICAL PROPERTIES OF METAL OXIDES

To evaluate electrical properties of metal oxides, conductivity should be considered. The degree of conductivity depends on the bandgap ( $E_g$ ). The term "bandgap" refers to the energy difference between the top of the valence band ( $E_v$ ) and the bottom of the c onduction band ( $E_c$ ) (in e lectron v olts) [52]. It is a n energy r ange i n a solid where no electron states can exist. A schematic of the basic bandgap model is shown in Fig. 2.7. This is equivalent to the energy required to free an outer shell electron from its orbit a bout the n ucleus to become a mobile c harge c arrier, a ble t o m ove freely within the solid material. The bandgap is therefore a major factor determining the electrical conductivity of a solid [53].





Fig. 2.7 Schematic of electrical conduction bands in materials [53]

Every solid has its own characteristic energy band structure and the variation in band structure is responsible for the wide range of electrical characteristics observed in various materials. In order for electrical charge to flow (i.e. current) in an oxide,

electrons must transfer from c ompletely f illed valence band levels across the bandgap and i nto the conduction b and. This r equires energy (work) to r aise the energy potential of the electron from  $E_v$  to  $E_c$ . If the bandgap is large, upon applying an external electric field at room temperature, there will be only a few electrons that have the necessary energy to j ump from the valence band to the conduction band. Increasingly temperature or supplying e nergy is thus required to provide e nough energy to elevate sufficient num bers of electron i nto the conduction band to thus increase electrical conductivity [53, 54].

To improve the electrical properties of metal oxides, doping is intentionally used. Doping introduces impurities into extremely pure (also referred to as intrinsic) metal oxides for the purpose of modulating its electrical properties. The impurities ar e dependent upon the type of metal oxide [11]. To evaluate how dopants may affect electrical properties of metal oxides, the term 'Conductivity' should be studied.

### 2.6.1 Conductivity

Electrical c onductivity ( $\sigma$ ) is that p roperty which relates the current d ensity in a material to the electrical field impressed across it at steady state as follows [54]:

$$\sigma = \frac{1}{R} \times \frac{d}{A} \tag{2-1}$$

where  $\sigma$  ( $\Omega$ .m)<sup>-1</sup> is the conductivity, A its area (m<sup>2</sup>), d its thickness (m), and R its electrical resistance ( $\Omega$ ). The electrical conductivity is a measure of the charge-arraying ability of material given by  $\sigma = nq\mu$  where

n = density of charge carriers (cm<sup>-3</sup>)

 $\mu$  = mobility of charge carrier (cm<sup>2</sup>/Vs)

q = charge (Coulombs, C)

The charge carriers may be either electrons ( $e^-$ ) or holes ( $h^\circ$ ), or cations (M) and/or anions (X). D epending on w hich c harge c arriers pr edominate, t he s olid m ay be classified as primarily an electronic (n- or p-type) conductor or an ionic conductor. However, mixed conduction occurs and this conduction is then represented as [54]:

$$\sigma = \sigma_{\text{electron}} + \sigma_{\text{ionic}} \tag{2-2}$$

Both t ypes of c onduction i nvolve t he pr esence of poi nt de fects i n t he c rystal structure and these are examined next.

# 2.6.2 Point Defects in Crystals

The conductivity is very closely related to the existence of point defects in crystals. Defects may be generated in a solid by (1) thermodynamic equilibrium (Schottky, Frenkel), (2) chemical substitution, (3) oxi dation or r eduction, a nd (4) e nergetic radiation. Defects m ay b e classified b eing e ither i onic d efects ( cation v acancies, cation in terstitials, a nion v acancies, a nd a nion in terstitials) o r e lectronic d efects (electrons and holes). In Table 2.4, Kroger-Vink [30] notation of the different types of defects are given.

The t hermodynamic va cancy (Schottky) and i nterstitual (Frenkel) de fects c an b e classified as inherent defects, since one or the other is always present in an ionic (crystal) so lid at all temperatures above ab solute zero [51]. E xtrinsic d efects ar e those defects present in an ionic solid as a result of doping with aliovalent ions and serve to preserve chemical stoichiometry.

Symbol	Definition
M <sub>M</sub>	Cation on regular lattice site
X <sub>X</sub>	Anion on regular lattice site
$V_{M}$	Cation vacancy
V <sup>"</sup> <sub>M</sub>	Effective charge on cation vacancy
$M_{i}$	Cation on interstitial site
$M_i^{\bullet \bullet}$	Effective charge on interstitial cation
X <sub>i</sub>	Anion on interstitial site
$X_{i}^{"}$	Effective charge on interstitial anion
V <sub>X</sub>	Anion vacancy
$V_X^{\bullet \bullet}$	Effective charge on anion vacancy
$h^{\bullet}$	Positive hole
<i>e</i> ′	Electron

 Table 2.4 Ionic defect symbol

The formation of these defects increases the configurational entropy of the solid, thereby d ecreasing t he o verall f ree en ergy. R elationships f or S chottky d efect formation may be given as:

$$M_M + X_X \to V_M'' + V_X'' \tag{2-3}$$

Schottky defects are typically formed in close-packed structures such as MO oxides. The cation and anion vacancies are considered to form separately and migrate to the surface of t he crystal, thereby i ncreasing the volume and d ecreasing t he d ensity. Relationships for Frenkel defects may be written as:

$$M_M \to M_i^{\bullet \bullet} + V_M''$$
 or  $X_X \to X_i'' + V_X^{\bullet \bullet}$  (2-4)

### 2.6.3 Defects in Metal oxides

Point defects that are formed in oxides as a result of equilibrium with the a gas phase ambient may occur by either oxygen deficiency (metal excess) or metal deficiency (oxygen excess) as follows [54]:

1) Oxygen deficiency (excess metal):

For such an oxide, the overall nonstoichiometric reaction can be written as

$$MO(s) \rightarrow MO_{1-x}(s) + \frac{x}{2}O_2(g)$$
 (2-5)

The oxygen vacancy is formed by the transfer of an oxygen atom on a normal lattice site to the gaseous shown as follows using Kroger-Vink notation:

$$O_o \rightarrow \frac{1}{2}O_2(g) + V_o^{\bullet \bullet} + 2e' \tag{2-6}$$

Since the vacancy has two trapped electrons, it can act as a donar and become singly or doubly ionized. This leads to n-type conduction at high temperature in such fixedvalence oxides as Al<sub>2</sub>O<sub>3</sub>, Ga<sub>2</sub>O<sub>3</sub>, etc. The free electrons may also become associated with variable-valence cations and the following reactions can occur:

$$M_M + V_O \to V_O^{\bullet} + M_M' \tag{2-7}$$

$$M'_{M} + V_{O}^{\bullet} \to V_{O}^{\bullet\bullet} + M''_{M} \tag{2-8}$$

Equation (2 - 7) is the more likely reaction and leads to n-type hopping conduction in such oxides as TiO<sub>2</sub>, Fe<sub>2</sub>O<sub>3</sub>, CeO<sub>2</sub>, etc.

In the case of excess metal atoms, such atoms may be found in the interstices:

$$M_M + O_O \to M_i^{\bullet \bullet} + \frac{1}{2}O_2(g) + 2e''$$
 (2-9)

The neutral M<sub>i</sub> atom can subsequently be ionized:

$$M_i \to M_i^{\bullet} + e' \tag{2-10}$$

$$M_i^{\bullet} \to M_i^{\bullet \bullet} + e' \tag{2-11}$$

Again, the singly ionized state is the more likely and leads to n-type conduction in oxides such as ZnO.

2) Metal deficiency (excess oxygen):

In an oxide (MO) cation vacancies can be formed through the reaction of ambient oxygen with the oxide.

$$\frac{1}{2}O_2(g) \to V_M'' + O_0 + 2h^{\bullet}$$
(2-12)

The holes present in the vacancy may be excited and transferred to other parts of the crystal:

$$V_M \to V_M' + h^{\bullet} \tag{2-13}$$

This condition leads to p-type conduction in such oxides as MnO, NiO, FeO, etc. As a valence defect, equation (2 - 13) can be written as

$$M_M + V_M \to V'_M + M_M^{\bullet} \tag{2-14}$$

With excess oxygen, neutral interstitial oxygen atoms may be formed thus:

$$\frac{1}{2}O_2(g) \to O_i \tag{2-15}$$

but this condition is not common in metal oxide lattices.

The relationship of oxygen partial pressure to conduction in metal deficient oxides can be illustrated as follows:

$$2M_{M} + \frac{1}{2}O_{2}(g) \to V_{M}'' + 2M_{M}^{\bullet} + O_{O}$$
(2-16)

The equilibrium constant, K<sub>T</sub>, for this reaction at temperature T is

$$K_T = \frac{[M_M^{\bullet}]^2 [V_M''] [O_O]}{(P_O)^{1/2} [M_M]^2}$$
(2-17)

where  $[O_0]$  and  $[M_M] \sim 1$  and  $V_M'' = \frac{1}{2}[M_M^{\bullet}]$ . Since  $\sigma$ , the conductivity, is proportional to  $[M_M^{\bullet}]$ , the following relationship can be derived:

$$\sigma = K P_{O_2}^{1/6} \tag{2-18}$$

Thus, if the  $P_{O_2}$  is increased, the conductivity a lso increases. In oxygen deficient oxides such as Ga<sub>2</sub>O<sub>3</sub> it can be shown, similarly, that the effect of increase in  $P_{O_2}$  is just the opposite, that is,

$$\sigma = K P_{O_2}^{-1/6}$$
 (2-19)

Depending on the oxygen partial pressure, therefore, n - or p -type c onduction may occur at very low and high  $P_{O_2}$ , respectively. For  $P_{O_2}$  ranges where the oxygen and metal v acancy co ncentrations are of si milar m agnitude, t he o xide is essen tially stoichiometric a nd i onic c onduction pr edominates [54]. A ll t hree t ypes of conductions a re exhibited by s uch oxi des ov er a w ide r ange of oxyge n pa rtial pressures.

# 3. Modeling and Si mulation: Theoretical S tudy o f El ectrical Properties

# 3.1 INTRODUCTION

To unde rstand t he r ole of dopa nts i n t he e lectronic pr operties of gallium oxi de, simulation and modelling of  $Ga_2O_3$  was performed using a type of software called Materials Studio. In this section,  $Ga_2O_3$ coatings were simulated using this software and its electronic properties was studied theoretically [55].

# **3.2 OBJECTIVE OF THEORETICAL WORK**

The o bjective of theoretical work with M aterials S tudio software is to s tudy the effect of adding different dopants on the electrical properties of  $Ga_2O_3$  structure. In particular, c hanging the lattice parameters and bandgap of  $Ga_2O_3$  is studied after

doping with  $Sn^{4+}$ ,  $Zn^{2+}$ , and  $W^{6+}$ . The justification for using these ions as dopants is that  $Sn^{4+}$ ,  $W^{6+}$ ,  $Zn^{2+}$  ions are close to  $Ga^{3+}$  in terms of ionic and covalent radius.

# 3.3 MATERIALS STUDIO SOFTWARE

Materials Studio is a flexible software environment for simulating and modeling the advanced materials. In this so ftware, the calculation and analysis of functions are performed using CASTEP. CASTEP is a program that employs density functional theory (DFT) to simulate the crystal s tructure and properties of a wide r ange of materials classes based on total energy. CASTEP takes the number and type of atoms in a system and predicts properties including lattice constants, structural properties, band structures, density of states, etc. [55-57].

CASTEP can be used effectively to study properties of both point defects (vacancies, interstitials, a nd s ubstitutional i mpurities) and e xtended d efects ( e.g. grain boundaries and dislocations) in semiconductors and other materials [56].

There are a number of steps involved in running a CASTEP calculation, which can be gr ouped a s two it ems [55,58]: structure de finition a nd c alculation s etup. Structure definition is a periodic 3D atomistic document containing the definition of the system of interest to be analysed. Once a suitable 3D structure document has been defined, the calculation setup is applied and then the type of calculation to be performed is selected and the associated parameters are set. Finally, the calculation that is to be run should be selected and the job initiated.

Final s tep which i nvolved i n a c alculation i s a nalysis of t he r esults. When t he calculation is complete, the files related to that j ob consist of results are analysed.

Some further processing of these files may be required to obtain observables such as electrical properties.

# 3.4 DOPING OF Ga<sub>2</sub>O<sub>3</sub> WITH Sn, Zn, AND W

# 3.4.1 Details of Calculation

The program can be done in five stages as follow:



Fig. 3.1 Flow chart of processing steps for simulation of Ga<sub>2</sub>O<sub>3</sub> structure [55]

First and second steps for modeling process shown in Fig. 3.1 a re do ne based on crystal s tructure k nowledge of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>structure. The bandgap and l attice parameter changes on the intrinsic  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> structure are calculated based on density function theory after adding different percentages of Sn, Zn, and W dopant elements.

The conductivity of the intrinsic  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> is to o poor to meet the requirements of applications. S electing appropriate doping elements to improve the electrical conductivity is very important.

At normal conditions, Ga<sub>2</sub>O<sub>3</sub> happens in the monoclinic ( $\beta$ ) phase, although it may be transformed into four other high-pressure and temperature polymorphs. $\beta$ -Ga<sub>2</sub>O<sub>3</sub> belongs to space group C2/m with the two-fold rotation axis  $\beta$  [59]. In the unit cell, $\beta$ -Ga<sub>2</sub>O<sub>3</sub> has two different Ga sites, denoted as Ga(1) and Ga(2), and three different O sites, denoted as O(1), O(2), and O(3). To plot the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> crystal structure using MS software shown in Fig. 3.2 (a), crystallography coordination (see Table 3.1) is required. B esides, u nit cell and l attice p arameters of t his m etal o xide sh ould b e considered. The unit cell can be characterized by four lattice parameters: *a*, *b*, *c*, and  $\beta$ . The Ga atoms are surrounded by O atoms in either tetrahedral Ga(1) or octahedral Ga(2) coordination.

Atomic site	Lattice positions					
	x	У	Z			
Ga(1)	0.1595	0.5000	0.3129			
Ga(2)	0.0912	1.0000	0.7957			
O(1)	0.1719	1.0000	0.5594			
O(2)	0.3303	0.5000	0.8914			
O(3)	0.9967	0.5000	0.2530			

**Table 3.1** Crystallography coordination of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>[59]

To dope the intrinsic  $Ga_2O_3$ , the Ga(2) atom is substituted by the dopant atom [58]. In this work, the crystal structure of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> was doped with Sn, W, and Zn shown in Fig. 3.2 (b, c, and d).

All t he cal culations w ere completed by CASTEP [59, 60]software package in Materials Studio Version 4.4 s oftware. In this software, choosing basic parameters for set up the program is another step. It should be chosen based on the quality type which is course, medium, and fine. The differences between qualities affect the rate and time of program (e.g. fine quality in this program is the most time-consuming work). In t his w ork, f ine quality was considered and based on t hat, t hese basic parameters were set up and run. After completing the program which took a time of 1 to 3 days for each program, the results are analyzed and the bandgap and changes in lattice parameters are obtained.



(a)



(b)

42



(c)



**Fig. 3.2** Crystal structure of (a) intrinsic Ga<sub>2</sub>O<sub>3</sub>, (b) Zn-doped Ga<sub>2</sub>O<sub>3</sub>, (c) Sn-doped Ga<sub>2</sub>O<sub>3</sub>, (d) W-doped Ga<sub>2</sub>O<sub>3</sub>

# 3.5 Simulation Results and Discussion

# 3.5.1 Geometrical structures

The ge ometry opt imization is shown as a diagram in Fig. 3.3. The equilibrium structure w as obtained after the c ell ge ometry and volume w ere fully r elaxed by minimizing the total energy and forces [52, 58].



Fig. 3.3 Energy optimization of Ga<sub>2</sub>O<sub>3</sub>

Before a dding di fferent pe rcentages of dopa nt t o  $Ga_2O_3$  structure, e nergy optimization is carried out (Fig. 3.3). The reason is to make sure that running the program is done a ccurately to obtain c onvergence. This di agram (Fig. 3.3) shows that there is a convergence and, thus the results are acceptable.

The calculated equilibrium lattice constants of the intrinsic and doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> are shown in Table 3.2. The results for intrinsic Ga<sub>2</sub>O<sub>3</sub> are similar to values reported in literature [19] indicating t hat choosing b asic parameters used in the model ar e completely matched with crystal structure and crystal project definition, and that the simulation has be en done correctly. For both, the lattice angles have not changed from literature [19] and little change exists in the lattice length.

The lattice parameters, crystal volume, and bandgap change of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> doped with the various dopants (3.125-12.5%) are tabulated in Table 3.2. Note that all dopant percentages are wt%.

Material	a (nm)	b (nm)	C (nm)	α	β	γ	V (A <sup>3</sup> )	$E_g(eV)$
Intrinsic Ga <sub>2</sub> O <sub>3</sub>	125.3	31.0	59.0	90	103.8	90	217.6	2.315
Reference[19]	122.3	30.4	58.0	90	103.8	90	217.7	2.190
3.125% Sn	132.1	33.0	60.2	90	103.6	90	236.9	1.600
6.250% Sn	132.5	33.1	60.2	90	103.4	90	240.1	1.097
9.375% Sn	133.3	33.3	60.4	90	103.3	90	244.2	0.665
12.50% Sn	134.0	33.5	60.7	90	103.5	90	247.2	0.215
3.125% Zn	132.9	33.2	60.1	90	103.6	90	237.5	2.260
6.250% Zn	132.3	33.0	59.8	90	103.4	90	236.1	1.415
9.375% Zn	133.2	33.3	60.0	90	103.4	90	238.4	0.945
12.50% Zn	134.0	33.4	60.0	90	103.0	90	238.8	0.445
3.125% W	132.0	33.0	60.3	90	103.6	90	237.7	2.100
6.250% W	134.9	33.7	60.3	90	103.4	90	246.0	1.600
9.375% W	132.1	33.3	60.4	90	104.3	90	244.2	1.450
12.5% W	No Convergence							

Table 3.2 Intrinsic and different concentration of dopants in Ga<sub>2</sub>O<sub>3</sub>

Fig. 3.4 and Fig. 3.5 present lattice parameter (a) and bandgap values as a function of changes of dopant percentage to compare the parameters' change in crystal structure of Ga<sub>2</sub>O<sub>3</sub>. No significant changes were observed for lattice parameters b and c.



Fig. 3.4 Changes in lattice parameter, a, vs. different percentage of dopants (wt%)



Fig. 3.5 Changes in bandgap vs. different percentage of dopants (wt%)

Fig. 3.4 s hows t hat t he l attice pa rameter, a , ha s t otally increased a fter dopi ng. Increasing to 3.175% of e ach dopants leads to an increase of 7 n m in this lattice parameter. For pe rcentage of dopa nts m ore t han 3.175%, c hanging i n l attice

parameter of Ga<sub>2</sub>O<sub>3</sub> crystal structure doped with Zn and Sn are almost similar to each other. However, for W the differences in lattice parameters are more pronounced. It might be due to the difference in ionic and covalent radii of Ga<sup>3+</sup> ion and W<sup>6+</sup> (see Table 3.3). Ionic and covalent radii of dopant ions should be comparable with Ga<sup>3+</sup> to be replaced with this main atom. The ionic (and covalent) size of Sn<sup>4+</sup>, Zn<sup>2+</sup> and Ga<sup>3+</sup>(shown i n T able 3.3) are v ery cl ose t o ea ch o ther, t hat i s 0.69 (1.41), 0.74 (1.22), and 0.62 (1.26) nm, respectively (from Pauling's ionic radii data). For W<sup>6+</sup>,

these values are 0.78 (1.62) nm which present a more deviation from  $\frac{R_{Ga^{3+}}}{R_{dopant}} = 1$  than

 $Sn^{4+}$  and  $Zn^{2+}$ . On the other hand, contribution of significantly different valence of  $W^{6+}$  from G  $a^{3+}$  on the lattice parameter c ould n ot be c onsidered ne gligible. A s a result, no convergence occurred when the weight percentage of W in Ga<sub>2</sub>O<sub>3</sub> structure increased to 12.5%.

Fig. 3.5 s hows the bandgap change in G  $a_2O_3$  crystal s tructure after doping with different percentages of Sn, Zn, and W elements. From this diagram, it can be seen that S n i ons pr esent more r eduction in the bandgap compared t ot he ot her investigated Zn and W ions. The bandgap in intrinsic G $a_2O_3$  is approximately 2.315 eV. It was r educed t o 1.6 after adding 3.125 % Sn i ons. T his i on c auses m ore decrease in bandgap i.e. from 1.6 to 0.215 eV when the amount of Sn concentration goes from 3.125% to 12.5%. This amount is much more compared to Zn and W ions. The cal culated bandgap for in trinsic G $a_2O_3$  is 2.315e V. Theoretical bandgap and experimental bandgap values have a large disparity. A s we know, the bandgap of intrinsic G $a_2O_3$  is almost 4.9 eV. This is because DFT theory is based on the ground state the coretically, resulting in th e e xchange–correlation potential be tween t he excited electronic that have been underestimated[57].

	Ga <sup>3+</sup>	Sn <sup>4+</sup>	Zn <sup>2+</sup>	W <sup>6+</sup>
Ionic Radius (Å)	0.62	0.83	0.74	0.78
Covalent Radius (Å)	1.23	1.40	1.22	1.62
$\frac{R_{Ga^{3+}}}{R_{dopant}}$	1.000	0.894	1.030	0.770

 Table 3.3 Ionic and covalent radius, and radii ratio of different elements [61]

On t he ot her hand, based on point defect chemistry [Kroger-Vink], explained in section 2.5.2,  $Z n^{2+}$ ,  $Sn^{4+}$ , and  $W^{6+}$  can go into the lattice as substitutional dopants.  $Sn^{4+}$  and  $W^{6+}$  may act as donors, while  $Z n^{2+}$  may act as an acceptor. The incorporation of S n, Z n, and W in G a<sub>2</sub>O<sub>3</sub> can be described by the following reactions:

$$ZnO \rightarrow Zn''_{Ga} + V_0^{\bullet \bullet} + O_0$$
 (4-1)

$$W_2 O_6 \rightarrow 2 W_{Ga}^{\bullet \bullet} + V_{Ga}'' + 6 O_0 \tag{4-2}$$

$$SnO_2 \rightarrow Sn_{Ga}^{\bullet\bullet} + V_{Ga}'' + 2O_0 \tag{4-3}$$

These d opants can d ramatically af fect t he el ectrical p roperties o f G  $a_2O_3$ . T he addition of Zn to G $a_2O_3$  increases the conductivity.



Fig. 3.6 Charges associated with a Sn dopant in Ga

Sn has four valence electrons, but Ga has only three valence electrons. Therefore, three electrons of the Sn form similar bonds with G a, and the fourth electron is available for conduction, indicating Sn is a donor dopant in  $Ga_2O_3$  (see Fig. 3.6).

Charges associated with a W ion in  $Ga_2O_3$  are shown schematically in Fig. 3.7. W has six valence electrons while Ga has only three valence electrons. Therefore, three electrons of the W form three localised bonds with oxygen, while the three electrons in excess are available for conduction, thus suggesting that W atoms act as donor dopants in  $Ga_2O_3$  (Fig. 3.8).



Fig. 3.7 Charges associated with a W dopant atom in Ga<sub>2</sub>O<sub>3</sub>



Fig. 3.8 Donor bond level in electrical conduction bond

The addition of Sn or W to  $Ga_2O_3$  is different from Zn. Zn has only two valence electrons; it can complete its bonds only by taking an electron from a Ga-Ga bond, leaving behind a hole in the Ga valence band. The positive hole is then available for conduction. Therefore, Zn atom is an acceptor because when ionized it accepts an electron from the valence band. The schematic for this electron exchange is shown in Fig. 3.9 and Fig. 3.10.



Fig. 3.9 Charges associated with a Zn atom in Ga



Fig. 3.10 Acceptor bond level in electrical conduction bond

In s ummary, t he effect of dopants on the electronic property of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> was analyzed. The introduction of the Sn and Zn caused the impurity energy level at the bottom of the conduction band. Therefore, the conductivity of the Zn-doped and Sndoped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> is basically improved compared to the intrinsic  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>.

# 4. Experimental Procedure

# 4.1 INTRODUCTION

As examined pr eviously, G  $a_2O_3$  coating d eposited on ceramic substrates such a s quartz via so l-gel r outes has be en r eported as pr omising c andidate f or many applications. In general, however, cracking of coatings at the drying stage of sol-gel processing is one of the main problems encountered in forming stable, thick coatings and is caused us ually by high shrinkage during drying and/or firing. To solve this problem, understanding the colloidal behaviour of gallium-oxide particles in solution and the f ormation of s table s ol is im portant. Ga<sub>2</sub>O<sub>3</sub> sol-gel pr ocessing i nvolving controlled hydrolysis a nd c ondensation, pe ptisation, gellation, drying a nd consolidation by a Ga-propoxide route is studied in this work.

### 4.2 OBJECTIVE OF EXPERIMENTAL WORK

The objective of the experimental work presented in this chapter was to develop  $Ga_2O_3$  sol-gel co ating l ayers on su itable ce ramic su bstrates su ch as quartz with minimal or no cracking on coating, and to investigate the structure and morphology of coating. The work involved two main areas of research. Firstly, the preparation of coating s olutions a nd t heir de position d rying a nd ge lation w ere i nvestigated. Secondly, the drying and heat-treatment of coating and the effect of heat-treatment parameters on the cracking behaviour of coating and microstructural during drying and firing w ere studied. A lso, incorporation of s uitable i ons, a s solid solution dopants for  $Ga^{3+}$  in  $Ga_2O_3$ , in the sol-gel process were investigated.

### 4.3 EXPERIMENTAL PROCEDURE

The general experimental procedure for sol-gel preparation of gallium oxide coatings on substrates (glass and quartz) is summarized in Fig. 4.1. Two procedures were used: Type-II sol based on a n aqueous route developed for  $Al_2O_3$  by Y oldas [38], and Type-I sol based on MOE. As explained later, sol-gel coatings prepared from the Type-I route d id n ot ge late (hence c ould not ge l c oherent c oatings) and this necessitated the developments of the non-aqueous route.



Fig. 4.1 Overall flow chart of experimental procedure [38, 47]

# 4.3.1 Preparation of Coating Solution

# Aqueous Route (sol Type-I)

As indicated in F ig. 4.1, a gallium mono-hydroxide (GaOOH) s ol for producing Ga<sub>2</sub>O<sub>3</sub> coating on substrate was prepared by a method similar to the method reported by Yoldas [38]. A total of 1.83 ml (0.01 mol) gallium-isopropoxide, < Ga(OC<sub>3</sub>H<sub>7</sub>)<sub>3</sub>, 99.9 wt% purity, Multivalent Lab. Co. UK >, w as slowly dripped into 20 ml (~1 mol) de-ionised stirred water held at temperature of 75°C. This was done in a sealed flask immersed in a c ontrolled-temperature s ilicon-oil b ath a nd f itted w ith a thermometer and condenser (Fig. 4.2). The solution was stirred continuously during the addition of gallium-propoxide and then for a further for 30 m inute to obtain a homogenous opa que s olution. T hen, 0.05 mL (0.2 mol) n itric a cid (H NO<sub>3</sub>, 70%, Sigma-aldrich) was added to peptize the hydrolysed solution, followed by stirring at 85-90°C for 24 hour s. After pe ptisation, the sol w as removed from the flask a nd stored in a sealed glass b ottle at r oom t emperature. The pH of this s olutions.

# Non-Aqueous Route (sol Type-II)

The above a queous technique based on Y oldas's method [38] did no t pr ovide a transparent uniform colloidal sol. Therefore, a non-aqueous method as explained in this s ection w as ut ilised. I n t his t echnique, a g allium-alkoxide s uch as ga llium-isopropoxide w as d issolved in a non -aqueous s olvent and s tabilizer ove r the temperature r ange of 60 -80°C. 2-Methoxyethanol (MOE) a nd m onoethanolamine (MEA) were used as the solvent and stabilizer, respectively. GaP was first dissolved in a mixture of MOE and MEA at 60°C using similar reaction set-up to the described

above (Fig. 4.2). The molar r atio of MEA to GaP was maintained at 1.0 a nd the concentration of GaP was 0.2 and 0.4 mol/L. After the solution was stirred for 1 h, a homogeneous and transparent solution was obtained. To provide a 50 ml of this sol, 3.65 ml of GaP w as a dded t o s olution of 45.0 a nd 1.5 ml of MOE a nd MEA, respectively. E xcess waste  $Ga(OC_3H_7)_3$  was diluted i n ethanol a nd then a dded t o excess w ater an d d isposed b y contract w aste disposal. Unwanted s ol-gel s olution was disposed by contract waste disposal.



Fig. 4.2 Schematic diagram of reaction equipment for Ga<sub>2</sub>O<sub>3</sub> sol

GaP is a corrosive material and is dangerous to skin and eyes, as well being flammable and s o precautions are essential for the storage and handling of this material. Containers which are opened must be carefully resealed to prevent leakage.

Also a bottle containing only a small quantity (<25g) of the chemical is kept and this bottle is sealed in side a larger plastic container. F or the solution preparation, the chemical was handled under an inert atmosphere of argon in a glove box or glove bag; with atmosphere being exhausted within a fume cupboard.

### 4.3.2 Preparation of doped Ga<sub>2</sub>O<sub>3</sub> Solution

Sol-Gel routes for preparing doped-Ga<sub>2</sub>O<sub>3</sub> have not been reported in the literature. The non-aqueous route described above (Type-II sol) was found to be successful for the pure G  $a_2O_3$  coatings and so was modified to incorporate dopant cations. The procedure is summarized in Fig. 4.3 [62, 63].



Fig. 4.3 Flow chart of sol-gel processing for preparation of doped Ga<sub>2</sub>O<sub>3</sub> solution

In these experiments, the precursors were first weighed out and then compound of dopants (nitrate or chloride) which were in the powder form were dissolved in MOE. In some work [10, 41, 63] isopropanol is used as solvent, but MOE was used here because it is a better solvent for gallium propoxide (GaP) than isopropanol. Gallium isopropoxide was incorporated into the mixture. The obtained solutions were stirred for 30 minutes in an open receptacle and kept at room temperature in air in order to yield a clear and homogeneous solution.

Since Gallium and aluminium are in a same group in the periodic table of the elements, and the chemical and physical behaviors of their oxi des are generally comparable with each other, a comparison between these two metal oxides were performed in terms of r esultant solutions with varied dopants. To compare doped  $Ga_2O_3$  and  $Al_2O_3$ , with the same method above mentioned, aluminium butoxide was used in the mixture instead of gallium isopropoxide.

To dope  $Ga_2O_3$  sol with different concentration of dopants, the dopants which would be compatible with  $Ga_2O_3$  had t of irst be determined. To choose dopants for a solution, besides the electronic preparation of the final ceramic structure, the ionic and covalent radius should be considered. In particular, an ionic / covalent radius of the dopant cation should be close to gallium, thus the dopant ions could go into the lattice as substitutional dopants. Table 4.1 lists Pauling's ionic and covalent radii data of some potential ions as dopants for  $Ga^{3+}$ .

	Ga <sup>3+</sup>	Sn <sup>4+</sup>	Zn <sup>2+</sup>	W <sup>6+</sup>	Mn <sup>2+</sup>	Cu <sup>2+</sup>	Al <sup>3+</sup>
Ionic Radius (Å)	0.62	0.83	0.74	0.78	0.72	0.73	0.53
Covalent Radius (Å)	1.23	1.4	1.22	1.62	1.17	1.17	1.18

**Table 4.1** Ionic and covalent radius of different ions [64]

According to data in table 4.1, the best ions as dopants for  $Ga^{3+}$  might be  $Zn^{2+}$ ,  $Mn^{2+}$ , and  $Cu^{2+}$ . Thus,  $Ga_2O_3$  solution was doped with these dopants. The reaction of these ions with  $Ga^{3+}$  resulted in a homogenous and transparent solution. The first issue that was faced was the suitability of the technique to make a solution of dopant and  $Ga^{3+}$ . Although, in simulation of  $Ga_2O_3$  using MS software, explained in section 3,  $Sn^{4+}$ ,  $W^{6+}$ ,  $Zn^{2+}$  ions have been chosen as dopants which are near  $Ga^{3+}$  in terms of ionic and covalent radius,  $Zn^{2+}$ ,  $Mn^{2+}$ ,  $Cu^{2+}$  were selected for this aim. It was due to the limitation of t ime a nd dopa nt c ompound a s w ell a s t he pr ecipitation i ssues of particles during the reaction. To compare the consistency between simulation results and experiment result, Zn-doped  $Ga_2O_3$  and pure  $Ga_2O_3$  coating were selected for the measurement. S ince d ifferent p ercentages of d opants w ere em ployed i n t he simulation, two varied percentages of Zn-doped  $Ga_2O_3$  (i.e. 3% and 6% of Zn) was produced for the measurement of bandgap on these coatings.

### 4.3.3 Deposition of Coatings

The substrates used in this work were quartz ( $\alpha$ -quartz; 15 mm d iameter x 1 mm thick disks; Highborn Co. Taiwan) and glass (soda-lime-silicate glass; 20 mm x 20 mm x 1 mm thick; Shanghai Machinery Import and Export Company, China). Prior to s ol-gel deposition, the substrates were degreased with s olvent (acetone) in a n
ultrasonic b ath a nd dr ied w ith c ompressed a ir. Then, s ols w ere de posited ont o substrate discs using a s pin coater (in-house unit, S chool of Materials S cience and Engineering, UNSW). The substrate was aligned with the centre of the spin coater. A syringe was used to deposit the prepared coating solution onto the substrate which was r otating a t m inimal s peed ( $\sim$ 5 r pm). T he s peed of t he s pin c oater t hen w as increased t o 1500 r pm and maintained a t t his s peed f or 3 0 s econds (Fig. 4.4) t o create a thin uni form c oating o n t he s ubstrate. T o b uild up va ried c oating thicknesses, sp in co ating w as performed i n sev eral times. A s ex plained l ater and based on SEM images, each spin coating layer was almost 50 nm.



Fig. 4.4 Schematic diagram of spin coating method

#### 4.3.4 Drying and Heat-treatment

After spin coating, coated substrates were dried slowly in air (25°C) for one hour to decrease the r isk o f c racking o n co ating d ue t o q uick ev aporation. T he dr ied substrates t hen heated at 90°C in an electrical oven for 10 min to evaporate the solvent, and then at 300°C for 20 min t o e liminate the organic c omponent in the coating. The dried coatings were then heated at 2 and 5°C/min to a soak temperature over 300 °C in an electrical m uffle furnace (Industrial H eating E ngineers, K iln Factory, NSW, AU). The thickness of the coating was estimated (using SEM) to be around 50-400 nm.

# 4.4 CHARACTERIZATION OF PREPARED SOLS

#### 4.4.1 Viscosity

The v iscosity m easurements w ere p erformed on Type-I and Type-II so ls using a Programmable R heometer, B rookfield m odel D V-III. T he m ain re sult of the sols and, characterization indicated the viscosity-time-temperature interactions in the sols and, in particular, the onset of gelation.

#### 4.4.2 FTIR (Fourier Transform Infrared Spectroscopy)

Structural evolution of sol-gel gallium oxide in solution was investigated on s cales of s everal l engths us ing i nfrared s pectroscopy. F TIR o f s ol t ype I a nd I I w ere performed using a spectrometer (Perkin-Elmer 2000).

### 4.5 CHARACTERIZATON OF COATED SAMPLES

## 4.5.1 Coating Morphology

The su rfaces of sam ples were inspected after each s tage of co ating and h eat treatment u sing reflected-light opt ical m icroscopy (Epiphot 600, N ikon, J apan) to evaluate the coating quality and, in particular, the extent of cracking.

### 4.5.2 Phase Composition

The phase composition of fired coatings on substrate discs were analysed using thin film X-ray diffraction (XRD; X'Pert PRO MRD, Philips diffractometer Model 1820 with  $CuK_{\alpha}$  0.15 nm at 45 KV/40mA). The incidence angle of the X-ray beam was either 0.8° or 2.0° and the scan range was 20°-80° using a step size of 0.02° at step duration of 1.5 seconds (0.8°/min).

The r esultant da ta w ere a nalysed using pr opriety s oftware (Traces v3.0, E MU, UNSW). The crystalline phases were identified according to phases contained in the ICDD Powder Diffraction File.

#### 4.5.3 Microstructure and Composition

The m icrostructures of the f ired co atings w ere ex amined u sing sc anning el ectron microscopy (SEM; Model S230, Hitachi, Japan) was used to examine the coatings at high m agnification ( >1000X). C oated su bstrates af ter h eating a t d ifferent temperatures (over 300°C) were sputter-coated with gold for SEM analysis. Energy-dispersive spectrometry (EDS) microanalysis (Oxford Instruments Link ISIS, EMU, UNSW) using SEM with an acceleration voltage of 10-15 kV was used to determine

the chemical composition of the fired coatings. At least five analyses at different spots were performed for each sample to obtain an average composition value.

# 4.5.4 Bandgap Measurement

The optical bandgap energy of sol–gel gallium oxide and Zn-doped Ga<sub>2</sub>O<sub>3</sub> coatings with different percentages (3% and 6%) was measured using an ultraviolet-visiblenear i nfrared sp ectrometer (Perkin E lmer U V/VIS/NIR Lambda 950). The transmittance spectrum of the coatings was recorded from 200 to 800 nm with the wavelength c orresponding t o t he opt ical ba ndgap be ing de termined by linear extrapolation of t he lower-wavelength por tion of t he pl ot t o z ero pe rcent transmittance. The optical bandgap was then calculated from this wavelength using Planck's e quation. Given t hat f or a lmost a ll i norganic s emiconductors, i ncluding Ga<sub>2</sub>O<sub>3</sub>, there is very little interaction between el ectrons and holes, the optical and electronic b andgap a re vi rtually identical and t hus the optical ba ndgap values measured in this work could be used reliably as values of the electronic bandgap.

# 5. Results and Interpretation

# 5.1 QUALITY EVALUATION OF SOLS

## 5.1.1 Viscometry

The result of viscometry and required time of sol for converting to gel are shown in Fig. 5.1. From these results, it can be found out that in less amount of time the Type-II sol could convert to gel. Type-I coated substrates were not able to form coating after drying and sintering. Based on this measurement, there is no gelation in Type-I sol a fter 16 0 m inutes while T ype-II s ol tended t o c onvert t o gel a fter a bout 60 minutes. This is in agreement with optical microscopy images and the SEM images shown in Section 5.2.



Fig. 5.1 Rheology behaviour of Type-I and Type-II sols

# 5.1.2 FTIR Results

All so lutions w ere ch aracterized by F T-IR s pectroscopy. Fig. 5.2 shows FT-IR spectra of selected samples which are Type-I and Type-II sols. The spectra of these sols show similar spectral features.



Fig. 5.2 Fourier Transform Infrared of Type-I and Type-II sols

A ve ry s trong a nd br oad ba nd a t 3404 a nd 3374cm<sup>-1</sup> can b e ass igned t o -OH stretching v ibrations o f H <sub>2</sub>O molecules. T he stretching b and of s tructural -OH groups is not separated due to strong overlap by the band at 3404cm<sup>-1</sup>. The IR band at 1452 cm<sup>-1</sup> is due to -OH bending vibrations of H<sub>2</sub>O molecules. The presence of the bands at 1371 a nd 1198 cm<sup>-1</sup> can be assigned to -COO vibrations which have been previously reported[27, 65]. The IR bands at 1125 and 1065 cm<sup>-1</sup> for sol type I and II can be assigned to  $\delta$  (OH) deformation vibrations. Therefore they c an be assigned to Ga–OH vibrations. Although viscosity results show that these s ols are completely different in terms of quality and converting to gel, structural evolution of these so Is a re n ot so d ifferent from each o ther. FTIR of s ols indicates that b and characteristic exist in sols are almost similar to each other in high wave numbers.

# 5.2 MICROSTRUCTURE OF COATED SAMPLES

## 5.2.1 Examination by Optical Microscopy

Figures 5.3 t o 5.7 s how t he r eflected-light o ptical m icroscope i mages o f so l-gel  $Ga_2O_3$  coatings pr oduced f rom t he t wo t ypes of s ols (I a nd I I) with va ried experimental parameters on glass substrates. Samples in Fig. 5.3 shows coating from Type-I sol and Fig. 5.4 to 5.7 show coatings from Type-II sol.

Fig. 5.3 shows the microstructure of sample heated for 2 h at different temperatures (300, 400, and 500°C) with heating rate of 2°C/min and predicted thickness of 400 nm. F ig. 5.4 s hows the microstructures of samples heated for 2 h at 300°C with different heating rates (2°C/min and 5°C/min) and different thicknesses (200 nm and 400 nm). This experiment was repeated for two other soak temperatures of 400°C

and 500°C with the same conditions of heating rate and sample thicknesses, which the resultant microstructures shown in Fig. 5.5 and 5.6, respectively.

For sam ples w hich were p rovided f rom s ol Type-I, t here w as a p roblem w ith forming the gel. Due to this problem, no coatings formed in substrate after heating in various temperatures (Fig. 5.3).





(b)



(c)

**Fig. 5.3** Sol-gel Ga<sub>2</sub>O<sub>3</sub> thin film, Type-I sol, heating rate of  $2^{\circ}$ C/min, 8 spin-coating layers (predicted thickness of coating is 400 nm) (a) heating at 300°C for 2 h, (b) heating at 400°C for 2 h, (c) heating at 500°C for 2 h

Coatings produced from the Type II (non aqueous sol) are now considered. As can be seen in Fig.5.4, for a soak time of 300°C, increasing heating rate and thickness of coatings tended to increase the extent of cracking in the coatings.



**Fig. 5.4** Sol-gel Ga  $_2O_3$  thin film, Type-II so l, o n g lass substrate, produced by heating at 300°C for 2 h as a function of heating rate (left Figures = 2°C/min, right Figures = 5°C/min) and coating thickness (upper Figures = 4 coating layers  $\approx$  200 nm, lower Figures = 8 coating layers  $\approx$  400 nm)

Samples heated at soak temperature of 400°C all show extensive coating. Also, the 'fragments' or 'flakes' of coating appear to have shrunk somewhat as evidenced by the gaps between them. As can be seen, the amount of cracks in coatings tended to increase with increasing heating rate and coating thickness.



**Fig. 5.5** Sol-gel Ga<sub>2</sub>O<sub>3</sub> thin film, Type-II s ol, o n g lass substrate, produced by heating at 400°C for 2 h as a function of heating rate (left Figures = 2°C/min, right Figures = 5°C/min) and coating thickness (upper Figures = 4 coating layers  $\approx$  200 nm, lower Figures = 8 coating layers  $\approx$  400 nm)

With i ncreasing the soak t emperature to  $500^{\circ}$ C (Fig. 5.6), the Ga<sub>2</sub>O<sub>3</sub> crystals a re formed (as XRD data presented later in this section). The formation of these crystals which are type  $\alpha$  of Ga<sub>2</sub>O<sub>3</sub>, characterised by XRD, is not homogeneous and uniform, and noticeable amount of cracks are observable in the final coatings.

 Heating rate = 2°C/min
 Heating rate = 5°C/min

 Image: Description of the strength of the strengt of the strength of the strength of the strengt

**Fig. 5.6** Sol-gel Ga<sub>2</sub>O<sub>3</sub> thin film, Type-II s ol, o n g lass substrate, produced by heating at 500°C for 2 h as a function of heating rate (left Figures = 2°C/min, right Figures = 5°C/min) and coating thickness (upper Figures = 4 coating layers  $\approx$  200 nm, lower Figures = 8 coating layers  $\approx$  400 nm)

From the a bove F igures, it is a pparent that the c oatings experienced a significant amount of cracking at each temperature for the 200 and 400 nm coating thicknesses.

A series of thinner coatings were prepared from the Type-II s ol u sing the slower heating rate of 2°C/min and thicknesses of  $\approx$  50 nm (one layer) and  $\approx$  100 nm (two layers). Compared with the 200 and 400 nm thick coatings, the 100 nm thick coating was much less cracked and the 50 nm thick coating was crack-free.



(a)



(b)

**Fig. 5.7** Type-II sol-gel  $Ga_2O_3$  thin film on glass substrate heated at 500°C for 2 h using a heating rate of 2°C/min: (a) 2 spin-coating layers (thickness of coating is 100 nm), (b) one spin-coating layer (thickness of coating is 50 nm).

From opt ical m icroscope i mages, i t c an be concluded that T ype-I s ol is n ot a satisfactory solution because it cannot form a gel in short time. Also, to have a freecrack  $Ga_2O_3$  thin film, heat-treatment c onditions such as heating rate and time are key f actors. W ith de creasing the heating r ate, t he amount of c rack i n s amples decreases c onsiderably. Since t he gl ass substrate cannot t olerate t he t emperature over 500°C, quartz ( $\alpha$ -quartz) was used as substrate for coating heated above this temperature.

#### 5.2.2 Examination by SEM

SEM was used to examine the morphology of coatings at magnifications higher than those pos sible w ith optical m icroscopy. SEM images of G  $a_2O_3$  thin f ilms (approximately 200 nm t hick) d eposited from Type-II sol and he at-treated as a function of heating rate and temperature are shown in Figures 5.8 and 5.9 for glass and quartz substrates, respectively.



**Fig. 5.8** Sol-gel Ga<sub>2</sub>O<sub>3</sub> thin film, prepared from Type-II sol on glass substrate, varied heating rate and heating temperature, 4 spin-coating layers (coating thickness  $\approx 200$  nm)



**Fig. 5.9** Sol-gel Ga<sub>2</sub>O<sub>3</sub> thin film, prepared from Type-II sol on quartz substrate, as a function of heating rate and heating temperature, 4 spin-coating layers (coating thickness  $\approx 200$  nm).

In general, the c oatings on t he g lass s ubstrates c ontain a s ignificant a mount of cracking and t he surfaces a ppear rough a nd distorted, the latter manifesting as obvious "ripples" in the s urface. T he c racks t end t o be r andomly or ientated a nd intersect each other of at distances of approximately 5  $\mu$  m. The ripples also appear to be randomly orientated and are approximately a few microns wide. The locations of the ripples do not seem to bear any relationship to those of the cracks. Despite the cracking and apparent roughness, the coatings appear to be well bonded to the glass substrate as evidenced by the lack of any apparent spalling or delamination. Given that the coatings are only ~200 nm thick, the ripples thus are interpreted as being in the coating and substrate together.

The co atings on t he q uartz substrates show so me cr acking b ut, u nlike t he g lass substrates, there are no ripples or distortion of the surface. Compared with the glass substrate, the extent of cracking is noticeably less on the quartz and the cracks tend to be spaced much wider apart (~30  $\mu$ m and greater) and are straighter. The effect of heating r ate w as more pr onounced i n t hat the f aster he ating r ate pr oduced significantly m ore cr acks. T he amount of cracking increased with he at-treatment temperature as did the width of the cracks (thus revealing the substrate below). At the highest temperature of 500°C, the coating at the edges of the cracks appears to have delaminated from the substrate.

The cause of the cracking for both substrate types and the apparent distortion of the glass substrates are interpreted in terms of the thermal mismatch between the  $Ga_2O_3$  coating and the substrate and the resultant stresses generated between the coating and the substrate during he at-treatment and subsequent cooling. T his is explained in detail in Section 6.2.

To evaluate the change in main elements' content in coating, EDS analysis using SEM was performed (Fig. 5.10). This analysis was carried out at least five times at different spots for each sample to obtain an average value and the results were the same as shown in Fig. 5.10. The Ga content compared to O, Au and Si content for resulting is given in this figure (Fig. 5.10). Using this analysis it can be shown that the amount of Ga after firing uniformly is constant in comparison to oxygen.



Fig. 5.10 EDS analysis of Sol-gel Ga<sub>2</sub>O<sub>3</sub> thin film

### **5.3 PHASE COMPOSITION**

Fig. 5.11 – 5.12 shows the XRD pattern of Ga<sub>2</sub>O<sub>3</sub> coating prepared with sol Type-II. It was noted that Ga<sub>2</sub>O<sub>3</sub>( $\alpha$ ,  $\beta$ ) basically can be prepared at high temperature (over 500°C) as r eported i n r ecent st udies[27, 65]. The cr ystalline p hases i n t he investigated samples were identified a ccording to the data c ontained in the ICDD Powder Diffraction File.

A selected thin film XRD pattern of  $Ga_2O_3$  coating on Quartz substrate which have been he at-treated at different temperatures (over 300°C) for 3 h are shown in Fig. 5.11. Quartz was identified as the major phase in a ll s amples. S o the diffraction intensity of  $Ga_2O_3$  phases is much lower than that of substrates while the intensity of the su bstrate p eaks r emained constant. U sing t hese p atterns w e ar e n ot ab le t o characterize the coatings.



Fig. 5.11 XRD pattern of Ga<sub>2</sub>O<sub>3</sub> thin film on quartz substrate

Precursor G  $a_2O_3$  phases be low 300°C in the thin f ilm X RD r esults where not apparent, because their different peaks are inherently low intensity, not being able to be discerned f rom the r elatively noisy background. D us to their relatively low intensity, the thin film XRD patterns were unsuitable for qualitative analysis of the Ga<sub>2</sub>O<sub>3</sub> phases.

The investigation of phase evolution in the coatings, independent of substrate, was examined by X-ray pow der di ffraction pa ttern of c oatings as a f unction of temperature. The diffraction patterns are shown in Fig. 5.12. It can be seen that coatings are essentially a morphous up to  $\sim 300^{\circ}$ C as indicated by t he lack of any significant diffraction peaks and the a morphous "hump" between 30° and 40° 2  $\theta$ . There are some very weak peaks, barely discernable above the background radiation, but which can be ascribed possibly to  $\alpha$ -Ga<sub>2</sub>O<sub>3</sub>. On further heating to 500°C,  $\alpha$ -Ga<sub>2</sub>O<sub>3</sub> peaks are clearly discernable, albeit relatively weak and broad. At 900°C, the only peaks that are present are due to  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> indicating that the  $\alpha$ -Ga<sub>2</sub>O<sub>3</sub> has fully transformed into  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>. Also, the 900°C pattern shows well-defined sharp peaks is  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> indicating that the coating is well crystallised. These observations are consistent with the phase transformation sequence for pure Ga<sub>2</sub>O<sub>3</sub> reported in the literature [13,16]. As explained in C hapter 2, complete crystallization of  $Ga_2O_3$ requires t emperatures a bove 870°C. T herefore, t he pr esence of s ome amorphous material in the as-prepared coatings and in coatings prepared at 300 and 500°C is consistent with this, as is the obtainment of  $100\% \beta$ -Ga<sub>2</sub>O<sub>3</sub> at 900°C.

Accurate determination of the lattice parameters of the  $Ga_2O_3$  phases from the XRD patterns in F ig 5.12 was n ot p ossible f or sev eral r easons. Firstly, r eliable determination of lattice p arameters requires a n in ternal standard to c alibrate the

goniometer angles of the diffraction peaks. However, it is not technically feasible to include a calibration s tandard i nto a (sol-gel) c oating. Secondly, the diffraction peaks need to be strong and sharp to enable accurate measurement of their angles. For the XRD patterns shown in Fig. 5.12, strong diffraction peaks occur only for the 900°C diffraction pattern and, whilst it may be possible to measure the peak angles to thus calculate the lattice parameters (of the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> phase), the lack of an internal standard w ould give que stionable reliability of the values obtained. For the XRD patterns ob tained f or coatings f ired a t lower te mperatures, the l ack of s trong diffraction peaks means that diffraction angles and hence lattice parameters can not be determined at all. Thus, ultimately, any effect of firing te mperature on lattice parameters cannot be made.



**Fig. 5.12**Characteristic parts of X-ray powder diffraction patterns of samples of as-prepared sol-gel and as a f unction of h eat-treatment of a soak t emperatures of 300, 500, 90 0°C (constant heating rate of 2°C/min)

#### 5.4 BANDGAP

The optical bandgap of pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, Zn3%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, and Zn6%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> coatings was measured by reflective spectroscopy in the spectral range of 300-800 nm as detailed in Section 4.5.4. P lots of reflection versus wavelength for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, Zn3%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, and Zn6%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> are given in figures 5.13 – 5.15. Extrapolation of the initial linear portion of each plot to zero reflectance gives the wavelength ( $\lambda$ ) of the corresponding optical bandgap energy for the allowed direct reflection. Extrapolation of the lin ear p ortion of e ach plot ga ve wavelengths for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, Zn3%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, and Zn6%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> of 270 nm, 280 nm, and 450 nm, respectively.

The optical bandgap energy  $(E_g)$  is then calculated using Planck's equation:

$$E_g = hc/\lambda$$

where:  $h = Planck's constant (6.626 \times 10^{-34} kg. m^2.s^{-1})$ 

 $c = speed of the light (2.998 \times 10^8 m.s^{-1})$ 

The calculation for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> for example (including conversion to eV) is:

$$E_g = hc/\lambda$$
  
= (6.626 × 10<sup>-34</sup> kg.m<sup>2</sup>.s<sup>-1</sup>) × (2.998 × 10<sup>8</sup> m.s<sup>-1</sup>) / (270 × 10<sup>-9</sup> m)  
x (1 eV/1.602 x 10<sup>-19</sup> kg.m<sup>2</sup>.s<sup>-2</sup>)  
= 4.50 eV

The sam e calculation for t he Zn3%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> and Z n6%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> coatings returned optical bandgap values of 4.42 eV and 2.75 eV, respectively. As explained in Section 4.5.4, the optical bandgap of almost all semiconductors can be taken to be identical to the electronic bandgap. This is true for Ga<sub>2</sub>O<sub>3</sub> and thus the optical bandgap values determined above were considered to be reliable values of the electronic bandgap for the pure and doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> coatings.



Fig. 5.13 Reflection vs. wavelength plot for pure Ga<sub>2</sub>O<sub>3</sub>



Fig. 5.14 Reflection vs. wavelength plot for Zn3%-doped Ga<sub>2</sub>O<sub>3</sub>



Fig. 5.15 Reflection vs. wavelength plot for Zn6%-doped  $Ga_2O_3$ 

# 6. Discussion

# 6.1 SOL-GEL DEPOSITION PROCESS

Two types of sols were prepared in this work using gallium isopropoxide as the starting precursor. The first sol (Type I sol) was prepared via a aqueous route based on the method developed by Yoldas for alumina sol-gel coatings. The other sol (Type II sol) was prepared via a non-aqueous route involving 2-methoxyethanol (MOE) as the solvent. The Type I sol did not gelate during the deposition process as evidenced by the lack of any visible coating on the substrates examined by optical microscopy (refer to Fig. 5.3). I n c ontrast, the Type I I s ol p roduced obvi ous coatings, a lbeit with varying extent of c racking de pending on the deposition and heat-treatment conditions. The viscometry results (refer to Figure 5.1) show that the Type II s ol e xhibited a pronounced and c ontinued increase in viscosity after  $\sim 60$ mins and this is attributed to gelation of the sol. The viscosity of the Type I sol on the other hand did not show any significant increase even after  $\sim 3$  hours and instead the sol remained highly fluid suggesting that gelation did not occur. It is likely that during spin coating deposition of the Type I sol the lack of gelation would result in the s ol be ing s imply s pun of f t he s ubstrate t hus r esulting i n t he a bsence of a ny discernible coating. Even if sol was present on the substrate following deposition it is likely that the water would have evaporated very quickly on s ubsequent drying thus precluding any gelation.

The lack of any obvious gelation in the Type I sol versus gelation in the Type II s ol c an be c onsidered i n terms of t he s olvation of the ga llium isopropoxide precursor in the solvents of water and 2-methoxyethanol, respectively, and the effect on reaction rates. In dissolving process the free energy change of solvent is very important. Since i n t he c hemical r eaction of s ol-gel G  $a_2O_3$  using ga llium isopropoxide with MOE or water, the ionization equilibrium of an acid or a base is affected by a solvent change, it needs to be considered in this process. Besides this theory, the effect of the solvent could be because of its dielectric constant and its ability to p referentially s olvate. A c hange in the solvating a bility or d ielectric constant can influence the acidity or basicity. From table 2.3, di electric constant of water at temperature of 25°C is about 5 times more than MOE. Therefore, water is more pol ar-solvent and i onization in water is greater than MOE. B ased on the practical experiment, it seems that these characteristic of water has made it as a solvent which is not suitable for Ga-based precursor, it is a proper solvent for Albased precursor though. It might be due to the difference in the evaporation rate of water compared to MOE. On the other hand, solvents can actually influence reaction rates and order of a chemical reaction and this is in agreement with what can be shown from the result of viscometry in Figure 5.1. The Type I sol is not considered hereafter since it was not capable of depositing a coating.

# 6.2 EFFECT OF CO ATING THICKNESS, H EAT TREA TMENT CONDITIONS, AN D S UBSTRATE TYPE O N CO ATING S TRUCTURAL EVOLUTION

The effects of the coating thickness, heat treatment conditions (heating rate and soak temperature), and substrate type on c oating formation and evolution of phase composition and microstructure are now discussed for the Type II sol. During spin coating, the Type II sol was able to spread out uniformly on the surface of substrate (glass) and to gelate to form a coherent coating. Subsequent heat treatment at 300°C for 2 hour s produced transparent coatings containing a network of fine cracks (see Figure 5.4 for coatings on glass substrates). The amount of cracking tended t o increase with i nereasing he ating rate (from 2 t o  $5^{\circ}$ C /min) and with increasing coating thickness (from 200 to 400 nm). It would be expected that during heating up to 300°C and then holding at this temperature, any residual solvent in the gelated coating would evaporate causing shrinkage of the coating. M oreover, it is likely that the evaporation of solvent at the coating surface would be faster than the rate of diffusion of solvent through the coating thereby establishing a concentration gradient of the solvent between the coating surface (lowest concentration) and the substrate (h ighest c oncentration). C oncomitant w ith t he e stablishment of t his concentration gradient would be a differential in the shrinkage of the coating across its thickness in that the highest shrinkage would be at the coating surface and the lowest s hrinkage w ould be a t t he c oating-substrate interface. T his d ifferential shrinkage would result in the coating surface being placed into a state of tension which, if exceeding the inherent tensile strength of the gelated coating, would cause cracking. The effects of heating rate and coating thickness can now be explained.

Increasing the heating rate should increase the rate of evaporation of solvent from the coating surface to a greater extent than the rate of solvent diffusion through the coating. This would increase, in turn, the magnitudes of the solvent concentration gradient, the differential shrinkage, and the tensile stress at the coating surface thus, ultimately, resulting in more extensive cracking of the coating. A s can be seen in Figure 5.4, the coatings he ated at the f aster heating r ate of 5°C /min ha d a f iner network of cracks c ompared with the coatings he ated at 2°C/min. Although not tested in this w ork, it is a nticipated that u sing s lower heating rates than 2°C/min should decrease the incidence of cracking.

Increasing the co ating thickness i ncreases the distance through which the solvent must diffuse to the surface or, in other words, increases the magnitude of the solvent concentration gradient. This increases the differential shrinkage and thus the tensile stress at the coating surface and ultimately increasing the extent of cracking in the coating. A s c an be s een in F igure 5.4, the ~400 nm thick coatings were noticeably more cracked than the ~200 nm thick coatings. Obviously, decreasing the coating thickness (by control of the sol-gel deposition process) should decrease the incidence o f c racking by de creasing the s olvent di ffusion di stance through the coating. In addition, as the coating gets thinner, the lateral shrinkage of the coating and the substrate. As a result, the coating tends to shrink "downwards" onto the substrate such that the lateral tensile stresses are reduced which, in turn, reducing the tendency of the coating to crack. A s shown in F igure 5.7 (for T ype II sol-gel coating thickness to the sol-gel coating the coating the tendency of 2°C/min), reducing the coating thickness to

100 nm greatly reduced the amount of cracking in the coating and further reducing the thickness to 50 nm resulted in crack-free coatings.

In the micrographs shown in Figure 5.4, it is apparent that there are instances of w here multiple c racks e manate f rom s pecific p oints in the c oatings. It i s speculated that these points may be minute defects in the coating such as bubbles or particulate inclusions (e.g. from dust) and that these defects act as initiation sites for crack propagation when the coating surface is placed into a state of tension.

Heat t reatment of t he coatings a t 400 a nd 50 0°C (Figures 5.4 a nd 5.6, respectively) re sulted in the a lready c racked c oatings u ndergoing further c racking and, i n a ddition, s ignificant s hrinkage of t he c oating "flakes". T he s hrinkage i s attributed to the loss of mass that would have occurred during the pyrolysis of the organic phase a nd a lso to the ons et of s intering a nd de nsification of the r esultant gallium oxide. Furthermore, it is apparent that there are areas of the coating in which the coating has delaminated and spalled from the substrate. The cracking, shrinkage, delamination, a nd s palling c ollectively r esult i n a s ignificant de crease i n t he "quality" of t he coating. O bviously, s uch coatings would not be s uitable f or a ny engineering or e lectronic a pplications. B y de creasing t he coating t hickness, t he above firing shrinkage tends to become restrained in the lateral directions (again, by virtue of whatever i nterfacial bo nding) s uch t hat t he coating t ends t o s hrink "downwards" ont o t he substrate t hereby r educing t he t endency of t he coating to crack. Coatings of Type II sol on glass heat treated at 500°C (using a heating rate of 2°C/min) were crack-free at a thickness of 50 nm.

It is apparent from SEM images of the coatings on glass (Fig. 5.8) that there are "ripples" in the coated substrate. The glass is a relatively low-temperature sodalime-silicate glass (used for microscope slides) and it is possible that the glass has softened at temperatures of  $\geq$ 300°C such that the compressive stress induced by the shrinking coating has effectively "pulled" the glass surface together thus creating the "ripples". Also, the coefficient of thermal expansion of the glass (~8-9 x 10<sup>-6</sup> °C<sup>-1</sup>) is significantly less than that of the Ga<sub>2</sub>O<sub>3</sub> coating such that the differential thermal contraction on cooling from ~300°C would result in the coating tending to exert a tensile stress in the glass near the glass surface. Given that the glass is relatively less stiff (Young's modulus ~ 70 G Pa) t han t he coating, this t ensile s tress c ould be relieved by the glass deforming or "rippling" at the surface.

The above "rippling" effect was not observed when quartz was used as the substrate which is reasonable since quartz would not be expected to soften much before i ts melting point. The coatings on the quartz substrates showed similar behaviour to those on the glass substrates in that the extent of cracking tended to decrease with d ecreasing h eat r ate (from 4 t o 2 °C/min) as shown in F ig. 5.9. However, c ompared with the coatings on gl ass substrates, the c oatings on qua rtz substrates were significantly less cracked at all heat treatment temperatures. This is attributed to two e ffects. F irstly, it is possible that the adherence of the sol-gel coating w as s tronger on t he quartz than on t he gl ass be cause of more crystallographic l attice match b etween co ating an d q uartz su bstrate compared t o coating and glass substrate, thereby making the coating more resistant to cracking and de lamination during shrinkage. Secondly, the thermal expansion coefficient of the q uartz is lik ely to b e s maller th an th e g lass s uch th at d ifferential expansion/contraction b etween the coating and the substrate on he ating/cooling is likely to be less for quartz compared with glass, thus resulting in less cracking.

# 6.3 EFFECT OF H EAT TREA TMENT CO NDITIONS O N CO ATING STRUCTURAL EVOLUTION

To characterise the phase evolution of sol-gel  $Ga_2O_3$  coating, a selected thin film XRD pattern of  $Ga_2O_3$  coating on Q uartz substrates which have been he attreated at different temperatures (300 - 900°C) for 3 h a re shown in Fig. 5.11 and 5.12.

The XRD pattern showed that coatings are essentially amorphous before heating to 300°C (Fig. 5.12). And the peaks would start to show after 500°C.

When samples heated at 500°C, it remained do minantly a morphous, but s howed faint diffraction lines of  $\alpha$ -Ga<sub>2</sub>O<sub>3</sub> and  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> which has been reported[27]. The same sample, upon heating at 900°C, was  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> with broadened diffraction lines. The Ga<sub>2</sub>O<sub>3</sub> phase in the pattern was  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> and the diffraction in tensity of this phase was always much lower than that of substrates. The intensity of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> peaks tended to increase with increasing heat treatment temperature and time while the intensity of the substrate peaks remained constant.

The broadening of X RD l ines of t he c rystalline phases d epended on t he M iller indices, t hus i ndicating an isotropic shapes of crystallites. T he r esults of X RD analysis showed a strong dependence of the phase composition of the samples on the experimental c onditions of t heir pr eparation. On t he ot her hand, G allium isopropoxide di ssolved i n M OE (Type-II s ol) would r esult in a completely amorphous phase, which upon heating at 900°C gave  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> as a single phase.

#### 6.4 EFFECT OF DOPANTS ON SOL-GEL Ga<sub>2</sub>O<sub>3</sub> COATING

Table 4.1 shows that  $Ga^{3+}$  is close to  $Zn^{2+}$ ,  $Mn^{2+}$ , and  $Cu^{2+}$  in terms of ionic and c ovalent r adius. T hus t hese ions c ould be potential ions a s dopants for  $Ga^{3+}$ based on w hat was explained in section 4.3.2. It supposed that making solution of these ions with  $Ga^{3+}$  using sol-gel technique would be easily possible. However, it was possible practically only for  $Cu^{2+}$  solution c ould r eact with gallium oxi de s ol and r esult in a hom ogenous solution. The reaction of other ions with gallium-base precursor led to precipitated solutions as indicated in Table 6.1.

**Table 6.1** Final s olution of pr ecursors a nd d opants (electronegativity values a re indicated in parenthesis)

dopant precursor	Zn <sup>2+</sup> (1.65)	Mn <sup>2+</sup> (1.55)	Cu <sup>2+</sup> (1.88)
Ga <sup>3+</sup> (1.81)	Р	Р	Н
Al <sup>3+</sup> (1.61)	Н	Н	NH

P=Precipitated

H= Homogenous transparent solution NH= Non-homogenous solution

To understand what happens in the chemical reaction of Ga-based precursor with other i ons, a comparison was performed with aluminium precursor (a luminium butoxide) which is similar to g allium alkoxide. A s mentioned g allium and aluminium are in a same group in the periodic table of the elements, and the chemical and physical behaviors of their oxides are generally comparable with each other in terms of morphology. Besides Ga, the dopant solution of alumina sol with the mentioned ions was made. As can be seen in Fig. 6.1, the result was interesting when the reaction of  $Zn^{2+}$  and  $Mn^{2+}$  solution with  $Al^{3+}$  were a homogenous solution without any precipitation. Interestingly, the reaction of  $Cu^{2+}$  with  $Al^{3+}$  was different from Ga<sup>3+</sup> and was not as homogenous as Ga<sup>3+</sup>.



**Fig. 6.1** Final solution of precursors and dopants: (A) Zn-doped Ga based precursor, (B) Cudoped G a based p recursor, (C) M n-doped Ga b ased p recursor, (D) Z n-doped Al b ased precursor, (E) Mn-doped Al based precursor, (F) Cu-doped Al based precursor

The re sults in dicate that t o f ind a s uitable dopa nt f or G a-based p recursor, electronegativity of cations in compound is an important factor to be considered. Just those dopa nts c ould be c ompatible f or t his t ype of pr ecursor that has electronegativity close to  $Ga^{3+}$ .

For doping a metal-oxide such as gallium oxide or alumina, the method is considered based on what explained in Fig. 4.3. To make a solution of dopant, the first issue was

technique t o make t he s olution a nd t he r eaction of most ions with ga llium-base precursor led to a precipitated solution (refer to table 6.1).

From the electronegativity data of elements, it can be shown that aluminium, zinc, and manganese are close to each other while it is al most similar for G allium and Cupper. That might be the fact that why  $Ga^{3+}$  could make a homogenous transparent solution with  $Cu^{2+}$  but other ions.

Electronegativity differences drive charge transfers on molecule formation. It is the chemical p otential of de nsity functional theory. W hile energy a nd no t electronegativity d etermines w hether a c hemical b ond w ill form, e lectronegativity differences determine t he c harge transfers w hich oc cur o n bond f ormation. T he method us ed f or t he pr eparation of a m etal a lkoxide de pends, i n ge neral, on the electronegativity of the metal.

The physical properties of metal alkoxides depend primarily on the characteristics of the metal t hat o ne of metal characteristic is its electronegativity besides v alence, atomic radius, and coordination number. Therefore, as discussed electronegativity of metal in metal alkoxide in volving in the chemical reaction p lays a big r ole and should be considered.

# 6.5 COMPARISON BET WEEN THEORETICAL AN D EXPERIMENTAL RESULTS

The effect of doping  $Ga_2O_3$  with  $Sn^{4+}$ ,  $Zn^{2+}$ , and  $W^{6+}$  cations was considered by simulation modeling using Material Studio software in Chapter 3 (see Table 3.2). It was shown that doping with increasing a mounts of these dopants gave systematic changes in the lattice p arameters of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> as well as the electronic bandgap

energy. F or t he l atter, e xperimental da ta f or one s elected dopa nt (Zn) was determined us ing r eflective s pectroscopy (see S ection 5.4) t hus e nabling a comparison of modeled and experimental bandgap energies. The values of modeled and e xperimental bandgap e nergies for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, Zn3%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, a nd Zn6%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> coatings are given in T able 6.2 be low and a re pl otted in Figure 6.2.

**Table 6.2** Comparison in bandgap energies for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, Zn3%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, and Zn6%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> coatings between simulated and experimental work

Samula	Bandgap (eV)		
Sample	Simulation	Experiment	
Ga <sub>2</sub> O <sub>3</sub>	2.32	4.50	
Zn3% doped	2.26	4.42	
Zn6% doped	1.42	2.75	



Fig. 6.2 Simulated and experimental bandgap energies for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, Zn3%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, and Zn6%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> coatings.

The bandgap data in Table 6.2 and F igure 6.2 s how that both the simulated and experimental bandgap energies decrease with increase concentration of Zn-dopant, consistent with the electronic d efect m odel as d iscussed earlier. However, the bandgap energies obtained by for the experimental coatings are consistently ~2 times higher than the c orresponding values obtained by s imulation. This disparity is attributed largely to the limitations in the simulation done using M aterial S tudio software. A s e xplained in C hapter 3, this s oftware employs density f unctional theory (D FT) for total e nergy to s imulate the crystal st ructure and associated properties. DFT is not a ble to incorporate all of the factors that contribute to the crystal/electronic s tructure and t ypically u nderestimates the value of the b andgap energy. Notwithstanding this, the software is a useful means of predicting trends in bandgap energy (and other electronic properties) and, in particular for this work, in confirming the effect on b andgap energy by the addition of dopant c ations to  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>.

Better comparison of the simulated and experimental bandgap data is obtained by normalising the values to the respective value for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>. The resultant data are shown in Figure 6.3. On this basis, the simulated values agree very well with the experimental values. The data show that the bandgap energy of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> is reduced by ~40% by the addition of 6% Zn cations. This indicates that the defect model used in the simulation is reasonable and in agreement with that indicated in the literature.



Fig. 6.3 Normalised si mulated and ex perimental b andgap en ergies f or pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, Zn3%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, and Zn6%-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> coatings. Values are normalised to the respective values for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>.
## 7. Conclusion

The o verall ai m o f t his t hesis w as t o d evelop a sol-gel s ynthesis r oute f or t he deposition o f pur e and doped gallium oxi de  $(Ga_2O_3)$  c oatings, to s tudy the pha se evolution in the coatings as a function of coating thickness and heat treatment time. Related t o this w as t he ai m t o evaluate t heoretically t he cr ystal st ructure an d electrical properties of coating doped with d ifferent percentages of v arious dopant ions by simulation and modelling of the intrinsic- and doped-Ga<sub>2</sub>O<sub>3</sub> structures using Materials Studio software, and to compare the theoretical results with experimental data.

In order to accomplish the aims of this work specified in chapter 1, the study was divided into the four (4) sequential stages of experimental work.

To de velop  $Ga_2O_3$  coating, two types of s ols were prepared in t his work using gallium isopropoxide as t he s tarting pr ecursor. T he f irst s ol (Type-I so l) was

prepared via an aqueous route based on the method developed by Yoldas for alumina sol-gel coatings. The other sol (Type-II sol) was prepared via a non-aqueous route involving 2-methoxyethanol (MOE) as the solvent. The principle of coating process was the deposition of these sols onto substrate (glass and quartz) by spin coating followed by drying and then heat treating at elevated temperature. The Type-I sol did not ge late during the deposition process as evidenced by the lack of any visible coating on the substrates. In contrast, the Type-II sol p roduced obvious coatings, albeit with varying extent of c racking de pending on t he deposition and he attreatment c onditions. The lack of any obvious ge lation in the Type-II sol v ersus gelation in the Type-II sol was considered in terms of the solvation of the gallium isopropoxide precursor in the solvents of water and 2-methoxyethanol, respectively, and the effect on reaction rates.

The effects of t he coating t hickness, he at t reatment c onditions (temperature and heating ra te), and s ubstrate type on t he conversion of the initial g allium-oxide precursor (sol) to  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> and the corresponding evolution of microstructure were studied. The initial deposited phase of gallium oxi de transformed to  $\alpha$ -Ga<sub>2</sub>O<sub>3</sub> and then to  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> with increasing temperature. At 500°C,  $\alpha$ -Ga<sub>2</sub>O<sub>3</sub> phase started to form and by 900°C,  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> was only stable phase of gallium oxide. Heat treatment (for 2 h) at different temperatures affected the c oating be haviour in terms of t he amount of c racking. T he a mount of c racking t ended t o increase with i ncreasing heating r ate a nd with i ncreasing c oating t hickness. Increasing the heating ra te in heat-treatment of c oating led to more extensive c racking of the coating. T his was mainly due to increase the rate of evaporation of solvent from the coating surface to a greater extent than the rate of solvent diffusion through the coating. The choice of substrates for Ga<sub>2</sub>O<sub>3</sub> was studied since it is critical and substantial for making high-

quality coatings. This study showed that quartz could be a compatible substrate for gallium oxide coating.

In this work, the effect of adding different do pants on the electrical properties of gallium oxi de c oatings w ere i nvestigated t heoretically us ing proprietary software called Materials Studio. The modeling of Ga<sub>2</sub>O<sub>3</sub> showed that the introduction of the Sn and Zn caused the impurity energy level at the bottom of the conduction band. Therefore, the c onductivity of the Zn-doped and Sn-doped  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>was improved compared to the intrinsic  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>. Also, the introduction of Sn and Zn to Ga<sub>2</sub>O with Also, to investigate which ions could be suitable as dopant for Ga<sup>3+</sup> in terms of solgel process, doping solution of these ions with Ga<sup>3+</sup> were made. Our study showed that to find compatible i ons as dopants for Ga<sup>3+</sup>, electronegativity of c ations are a key factor. Just those dopants could be compatible for this type of precursor that has electronegativity close to G a<sup>3+</sup>. This ion (Ga<sup>3+</sup>) could m ake a hom ogenous transparent s olution just with Cu<sup>2+</sup> but ot her i ons and this showed that the ba sic theory a bout e lectronegativity is a n i mportant c onsideration i n de veloping s ol-gel routes for doped-gallia, and doped-oxides in general.

The opt ical bandgap energy was determined experimentally for s ol-gel produced coatings of pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>, Zn3%-doped Ga<sub>2</sub>O<sub>3</sub>, and Zn6%-doped Ga<sub>2</sub>O<sub>3</sub>. L ike the simulated v alues, the experimental v alues decreased w ith i ncreasing Z n d opant amount thus suggesting that the structural model used to simulate the Ga<sub>2</sub>O<sub>3</sub> and the role of dopants in the electronic bandgap structure were fundamentally correct. The structural model and the bandgap data indicate that the  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> is monoclinic and that t he Z n dopa nts f rom a substitutional s olid s olution w ith t he Ga<sub>2</sub>O<sub>3</sub>. The experimental value of the bandgap energy for pure  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> agreed reasonably well with values reported in the literature and the experimental values for the pure and

doped coatings were consistently  $\sim 2$  times higher than the simulated values which suggested t hat t he structural m odel us ed t o c alculate t he ba ndgap energies systematically underestimated the values. This was attributed to limitations in the structural model. R egardless, the structural model w as considered r eliable f or predicting the effects of d opants on selected structural and electronic properties of Ga<sub>2</sub>O<sub>3</sub>.

## 8. Future work

Future w ork in this field c an b e c arried o ut in two d ifferent d irections, firstly by overseeing the new de velopments in the c omputational a spects and s econdly by following up the results obtained in this thesis in the term of experimental condition. The st able  $\beta$ - Ga<sub>2</sub>O<sub>3</sub> phase gallium oxi de is formed at temperatures over 870°C. Seeding with other m etal-oxides in the sol-gel process, as done with alumina for example, may be a potential m ean of s ignificantly l owering the crystallisation temperature of gallium oxide as well as giving transformation directly to the high temperature  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> phase. A lso, further w ork c ould be done on e xamining the cross-sectional m icrostructure of the co atings by T EM to investigate in d etail the coating-substrate interface an d, i n particular, a ny di fferences i n t he bondi ng characteristics of the coating with the two different substrates of glass and quartz.

## 9. References

- Shan, F., Liu, G., Lee, W., K im, S., Structural, e lectrical, and opt ical properties of transparent gallium oxide thin films grown by plasma-enhanced atomic layer deposition. Applied Physics, 2005. 98: pp. 023504-023510.
- 2. Hu, J., Li, Q., Meng, X., Lee, C., Lee, S., Synthesis of  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> nanowires by *laser ablation*. Phys. Chem. B, 2002. **106**: pp. 9536–9539.
- Passlack, M., Schubert, E., Hobson, W., Hong, M., Moriya, N., Chu, S., Konstadinidis, K., Mannaerts, J., Schnoes, M., and Zydzik, G., *Ga<sub>2</sub>O<sub>3</sub> films for e lectronic and opt oelectronic a pplications*. Journal of A pplied P hysics, 1995. 77: pp. 686-693.
- Li, Z., Moodera, J., Gallium ox ide as an i nsulating b arrier for spindependent tunneling junctions. Applied Physics Letters, 2000. 77: pp. 3630-3633.
- 5. Binet, G., *Origin of the blue luminescence of*  $\beta$ -*Ga*<sub>2</sub>*O*<sub>3</sub>. Applied P hysics Letters, 1998. **59**: pp. 1241-1249.
- Fleischer M., *Electron mobility in single and polycrystalline Ga<sub>2</sub>O<sub>3</sub>*. Applied Physics Letters, 1993. **74B**: pp. 300–305.
- Ogita, M., Nakanishi, Y., Hatanaka, Y., *Ga<sub>2</sub>O<sub>3</sub> thin film for oxygen sensor at high temperature*. Applied Surface Science, 2001. 175: pp. 721-725.
- Fleischer, M., Sensing reducing gases at high temperatures using long-term stable Ga<sub>2</sub>O<sub>3</sub> thin films. Sensors and Actuators, 1992. 6: pp. 257-261.

- 9. Fleischer M., *Sensing Gallium ox ide t hin f ilms: a ne w m aterial f or hightemperature oxygen sensors.* Sensor and Actuators, 1991. **B4**: pp. 437-441.
- Li, Y., Wlodarski, W., Galatsis, K., Kalanter-Zadeh K., *Investigation of the oxygen gas sensing performance of Ga<sub>2</sub>O<sub>3</sub> thin films with different dopants.* Sensors & Actuators, 2003. **B 93**: pp. 431-434.
- 11. Ueda, N., Waseda, R., Kawazoe, H., *Anisotropy of electrical and o ptical properties in*  $\beta$ -*Ga*<sub>2</sub>*O*<sub>3</sub>. Applied Physics Letters, 1997. **71**: pp. 933-935.
- Hao, J., Optical and luminescent properties of undoped and rare-earth-doped Ga<sub>2</sub>O<sub>3</sub> thin films deposited by spray pyrolysis. Applied Physics Letters, 2002. **35**: pp. 433-438.
- Roy R., Osborn, E., *Polymorphism of Ga<sub>2</sub>O<sub>3</sub> and the System Ga<sub>2</sub>O<sub>3</sub>-H<sub>2</sub>O*.
  American Ceramic Society, 1952. 74: pp. 719-722.
- 14. Ahman J, Svensson, G., Albertsson, J., *A reinvestigation of*  $\beta$ -*Ga*<sub>2</sub>*O*<sub>3</sub> *oxide*, Acta Crystallogr., 1996. **C52**: pp. 1336-1338.
- Matsuzaki, K., Kamiya, T., *Field-induced c urrent m odulation i n e pitaxial film o f d eep-ultraviolet t ransparent o xide sem iconductor Ga<sub>2</sub>O<sub>3</sub>. Applied Physics Letters, 2006. 88: pp. 092106(1/3).*
- Qian, H., Zhang, Y., Lin, G., Zheng, J., Xu, R., *Template-free synthesis of highly uniform α-GaOOH spindles and conversion to α- Ga<sub>2</sub>O<sub>3</sub> and β-Ga<sub>2</sub>O<sub>3</sub>.
  Crystal Growth, 2008. 8: pp. 1282–1287.*
- Laubengayar, A., *The sesquioxide and hy droxides o f g allium*. American Ceramic Society, 1939. 61: pp. 1210-1214.

- 18. Machon, D., Xu, B., Dong, J., *High-pressure study of the* α-*to* β- *transition in*  $Ga_2O_3$ . Physical rev., 2006. **B 73**: pp.352-363.
- Yoshioka, S., Kuwabara, A., Oba, F., Matsunaga, K., Tanaka, I., *Structures and energetics of Ga<sub>2</sub>O<sub>3</sub> polymorphs*. Physics Condensed Matter, 2007. 19: pp. 346211-21
- 20. Fleischer, M., *Characterization a nd cryst allite g rowth o f sem iconducting high-temperature-stable Ga<sub>2</sub>O<sub>3</sub> thin fi lms.* Materials Science L etters, 1 992.
  11: pp. 1728-1731.
- Battiston, G., Porchia, M., Bertoncello, R., Caccavable, C., *Chemical vapour deposition and characterization of gallium oxide thin films* Thin Solid Films, 1996. 279: pp. 115-118.
- Orita, M., Hirano, M., *Deep-ultraviolet transparent conductive β-Ga<sub>2</sub>O<sub>3</sub> thin films*. Applied Physics Letters, 2000. 77: pp. 4166-4168.
- 23. Fleischer, M., *Thin-film gas s ensors bas ed o n hi gh-temperature-operated metal oxides*. Vacuum Science and Technology, 1999. **17**: pp. 1866-1872
- Passlack, M., Mannaerts, J., Quasistatic and hi gh f requency c apacitance– voltage c haracterization of Ga<sub>2</sub>O<sub>3</sub>–GaAs st ructures f abricated b y i n si tu molecular beam epitaxy. Applied Physics Letters, 1996. 68: pp. 1099
- Marie, P., Cardin, J., *Growth and characterization of gallium oxide thin films* by r adiofrequency m agnetron s puttering. Phys. S tat. S ol., 2008. 205: pp. 1943–1946.
- 26. Kokubun, Y., Sol-gel p repared  $\beta$ -Ga<sub>2</sub>O<sub>3</sub> thin films for u ltraviolet photodetectors. Applied Physics Letters, 2007. **90**: pp. 031912-1/3.

- Ristic, M., Music, S., *Application of s ol-gel method i n t he s ynthesis of gallium oxide*. Materials Letters, 2004. 59: pp. 1227-1233.
- 28. Sinha, G., Chaudhuri, S. , Sol-gel derived phase pure α-Ga<sub>2</sub>O<sub>3</sub> nanocrystalline t hin film and i ts o ptical pr operties. Crystal G rowth, 2005.
  276: pp. 204-207.
- 29. Binions, R., Carmalt, C., *Gallium o xide thin fi lms fr om th e a tmospheric pressure chemical v apor de position r eaction of ga llium t richloride and methanol.* Chemistry and Materials, 2004. **16**: pp. 2489-2493.
- Aggarwal, S., Ramesh, R., Point defect chemistry o f metal o xide heterostructures. Annual Reviews in Materials Science, 1998. 28: pp. 463-499.
- 31. Yamaga, M., *Donar structure and electric transport mechanism in β-Ga<sub>2</sub>O<sub>3</sub>*.
  Physical Review B, 2003. 68: pp. 431-443.
- 32. Wahl, K., Dunn, D., Singer, I., *Effects of ion implantation on microstructure, endurance and wear behavior of IBAD MoS*<sub>2</sub>. Wear, 2000. **237**: pp. 1–11.
- Bae, I., *Phase and m icrostructural development in alumina sol-gel coatings* on CoCr alloy. Materials Science: Materials in Medicine, 2004. 15: pp. 959-966.
- 34. Lange, F., *Powder p rocessing s cience a nd t echnology f or i ncreased reliability*. American Ceramic Society, 1989. **72**: pp. 3-15.
- Brinker, C., Scherer, G., Sol-Gel Science: The Physics and Chemistry of Sol-Gel Processing. 1990, Academic Press Inc.
- 36. Rahaman, M., *Ceramic Processing and Sintering*: 1999, Marcel Dekker Inc.

- Haneda, M., K intaichi, Y., Selective reduction over Ga<sub>2</sub>O<sub>3</sub>-Al<sub>2</sub>O<sub>3</sub>: effect of sol-gel method, Catalysis, 2000. 192: pp. 137-148.
- Yoldas, B.E., *Hydrolysis of aluminum al koxide and bay erite c onversion*.
   Applied Chemical Biotech., 1973. 23: pp. 803.
- Fathollahi, V., Amini, M., Sol-gel preparation of highly oriented gal liumdoped zinc oxide thin films, Materials Letters, 2001. 50: pp. 235-239.
- Bae, J., Development of Nanostructured Alumina Sol-Gel Coating on CoCr Biomedical Alloy. 2004, PhD thesis, UNSW.
- 41. Haneda, M., Kintaichi, Y., Selective r eduction o f N O w ith p ropene o ver Ga<sub>2</sub>O<sub>3</sub>-Al<sub>2</sub>O<sub>3</sub>: effect of sol-gel method on the catalytic performance. Journal of Catalysis. 2000. 192: pp. 137–148.
- 42. Niederberger, M., Pinna, N., *Metal Oxide Nanoparticles in Organic Solvents*.2009: Springer, New York.
- Eldik, R., Advances in Inorganic Chemistry. Vol. 60. 200 8: Elsevier Inc. Amsterdam.
- 44. Mitzi, D., *Solution Processing of Inorganic Materials*. 2009: Wiley, New York.
- Flynn, A., *Inorganic C hemistry*. 2009: G lobal M edia, Horsham, West Sussex.
- 46. Ristic, M., Popovic, T., Music, S., *Application of sol-gel m ethod i n t he synthesis of gallium(III)-oxide*. Materials Letters 2005. **59**: pp. 1227–1233.

- 47. Kokubun, Y ., Miura, K ., Sol-gel pr epared be ta G a<sub>2</sub>O<sub>3</sub> thin f ilms fo r ultraviolet phot odetectors. Applied P hysics L etters, 2007. 90: pp. 031912 (1/3).
- 48. Roy, R., Hill, V., Osborn, E., *Polymorphism of Ga<sub>2</sub>O<sub>3</sub> and the system Ga<sub>2</sub>O<sub>3</sub>-H<sub>2</sub>O.* J. Am. Cer. Soc., 1952. **71**: pp. 719-722.
- 49. Das, B., Roy, R., *Thermodynamics of the GaCl<sub>3</sub>–HCl–H<sub>2</sub>O system at 258°C*.
  Solution Chemistry, 2000. 29: pp. 289-297.
- Levin E., *Phase Diagrams for Ceramics*. The American Ceramic Society, 1964. pp. 321-323.
- Schock, R., *Point Defects in Minerals*. Geophysical Monongraphs, 1985.31: pp. 232-245.
- 52. Unger, I., Mohamed, M., *The surface band structure of*  $\beta$ -Ga<sub>2</sub>O<sub>3</sub>-software. Journal of Physics: Conference Series, 2011. **286**: pp. 342-348.
- 53. Moulson, A ., Herbert, J ., *Electroceramics M aterials, P roperties, Applications.* 2003, John Wiley & Sons Ltd.
- 54. Buchanan, R., *Ceramic M aterials f or E lectronics: p rocessing, p roperties, and applications.* 1991, Marcel Dekker, Inc.
- 55. Hasnip, P., A Beginner's Guide to Materials Studio and D FT Calculations with Castep. 2007, York University, UK.
- 56. Segall, M., Lindan, P., *First-principles simulation: ideas, i llustrations and the CASTEP code.* Condensed Matter, 2002. **14:** pp. 2717–2744.

- 57. Milman, V., Refson, K., *Electron and vibrational spectroscopies using DFT*, *plane w aves and ps eudopotentials: C ASTEP i mplementation*. Molecular Structure, 2010. **10**: pp. 1113-1114.
- 58. He, H., Orlando, R., *First-principles study of the structural, electronic, and optical p roperties o f Ga<sub>2</sub>O<sub>3</sub>-software.* Physical R eview B, 2006. 74: pp. 1143-1148.
- 59. Ohira, S., Suzuki, N., Characterization of t ransparent and c onducting Sn-doped β-Ga<sub>2</sub>O<sub>3</sub> single crystal after anne aling-software. Thin S olid F ilms, 2008. 516: pp. 5763–5767.
- 60. Yamaga, M., *Donor st ructure and electric transport mechanism in Ga*<sub>2</sub>O<sub>3</sub>*software.* Physical Review B, 2003. **68**: pp.1157-1162.
- 61. Pauling, L., *The nature of the chemical bond and the structure of molecules and crystals.* 1960, Cornell University.
- 62. Zhu, Y., Zhang, L., The chemical states and pr operties of doped TiO film photocatalyst prepared using the Sol–Gel method with TiCl as a precursor. Applied Surface Science, 2000. 158: pp. 32–37.
- Bai, S., T. T seng, *Effect of al umina dopi ng on s tructural, e lectrical, and optical properties of sputtered ZnO thin films*. Thin Solid Films, 2006. 515: pp. 872–875.
- 64. Patnaik, P., *Handbook of Inorganic Chemicals*, 2003, McGraw-Hill, Ne w York.
- Bradley, S., Kydd, R., Yamdagni, R., Detection of a new polymeric species formed t hrough t he hydrolysis of G allium(III) Sal t So lutions. Chem. S oc., 1990. 2: pp. 414-417.